

# Silicon Photonics for HEP experiments

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EP-ESE Seminar  
09.04.2019

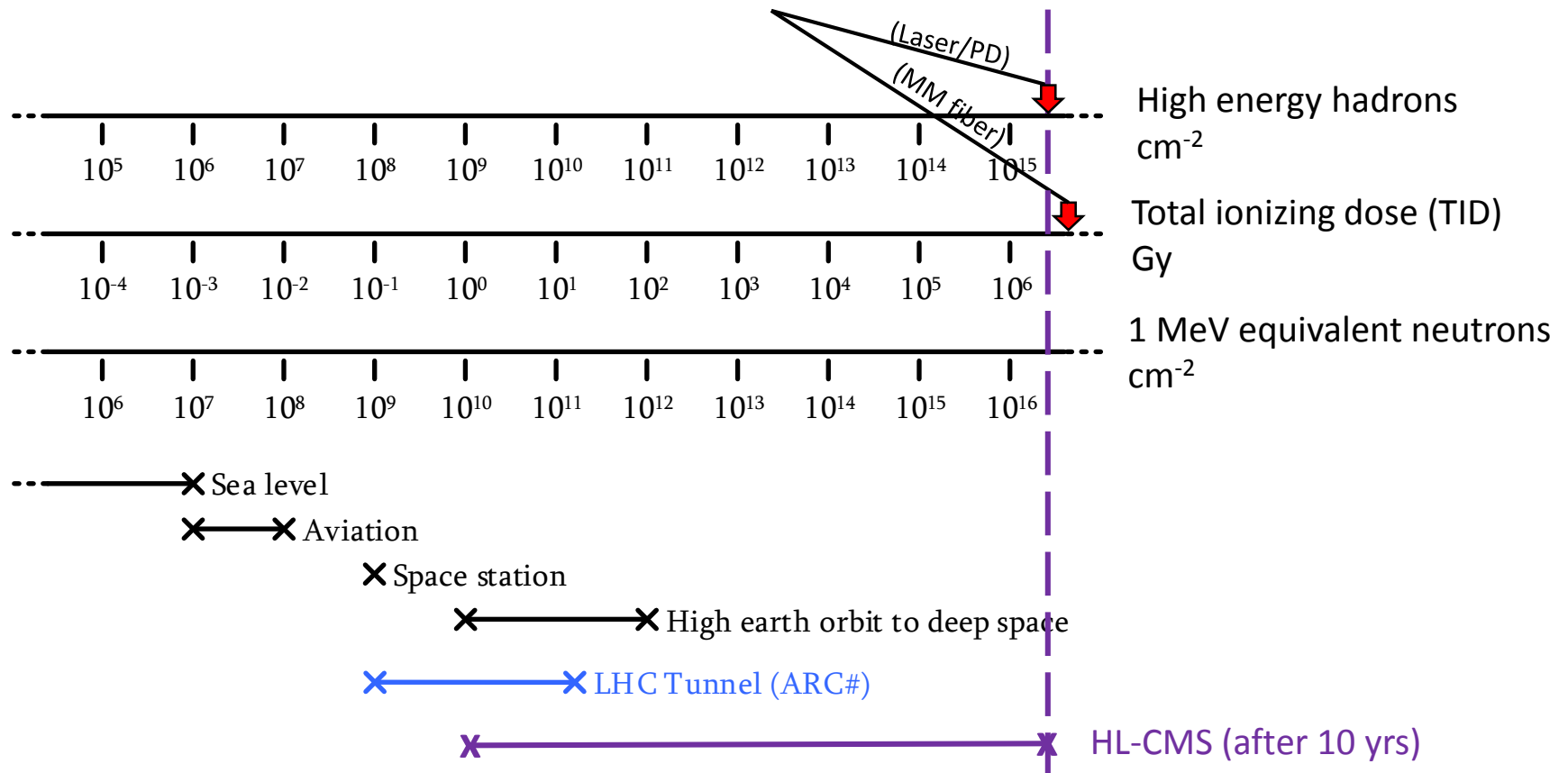
# Outline

- Reminder: Why are we investigating Silicon Photonics?
- Reminder: What is Silicon Photonics and how does it work?
- Testing of radiation resistance of Silicon Photonics devices
- Next steps



# Radiation resistance of optical links

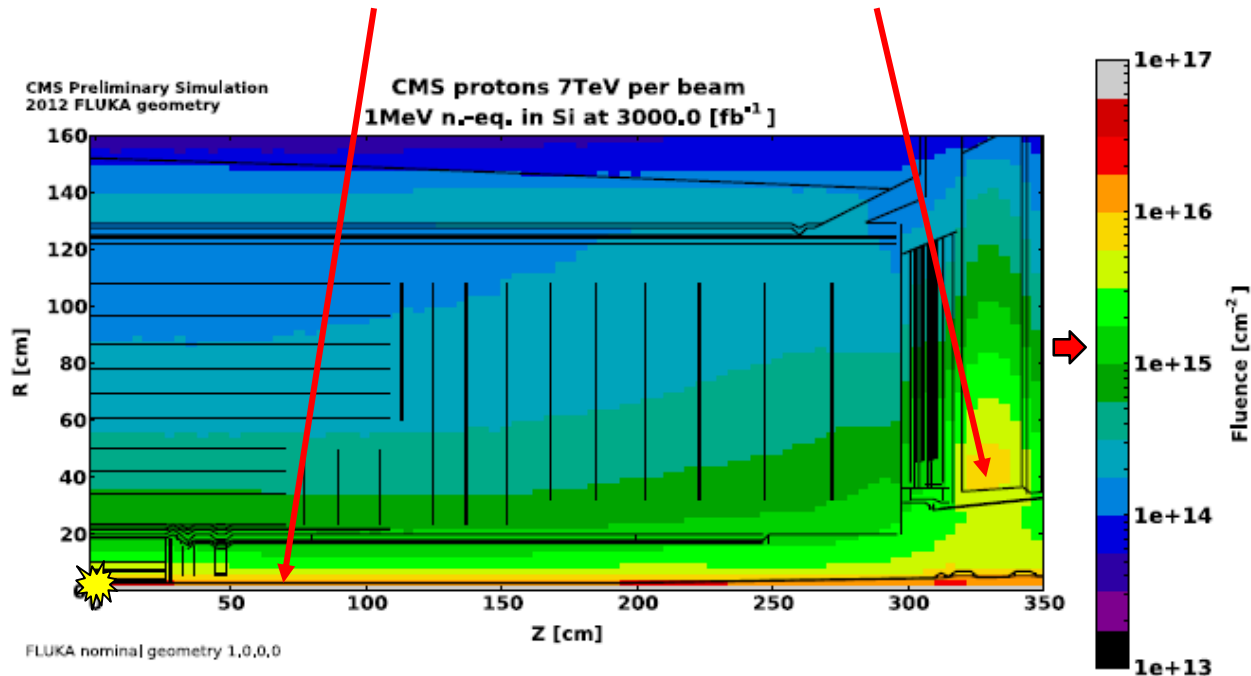
Current optical links (including newest developments)



# Motivation to investigate Silicon Photonics

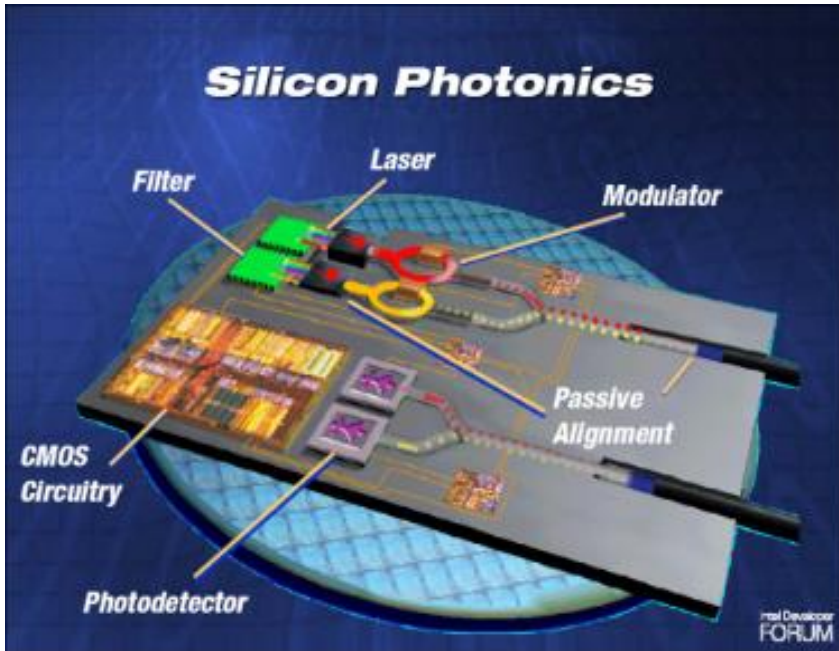
A) VL and VL+ reach their limits with the end of HL-LHC

B) No solution for extreme areas, so far: Cu-links



C) Because of space restraints in the innermost detector region highly integrated links are needed

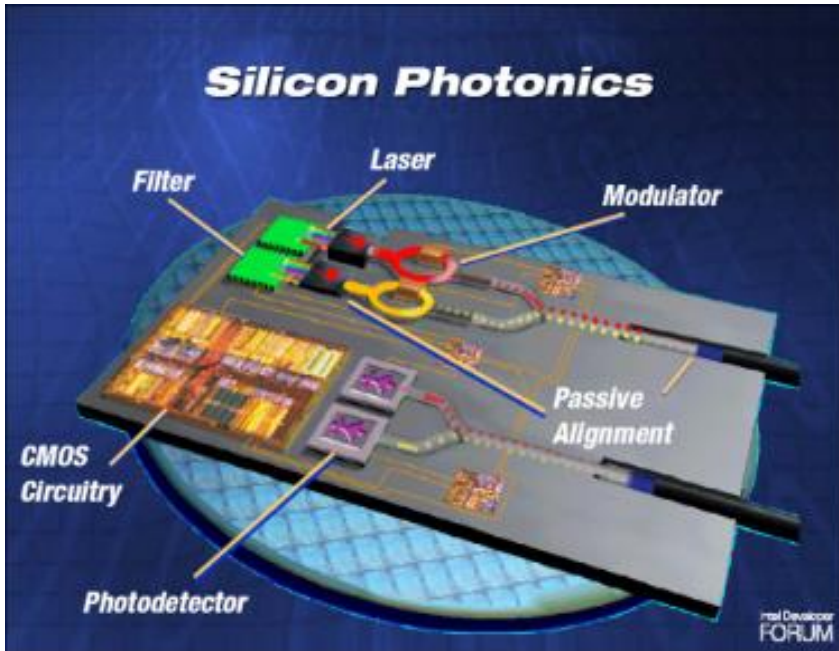
# What is Silicon Photonics?



from: <https://ic.tweaking.net/ext/i.dsp/1109883395.png>

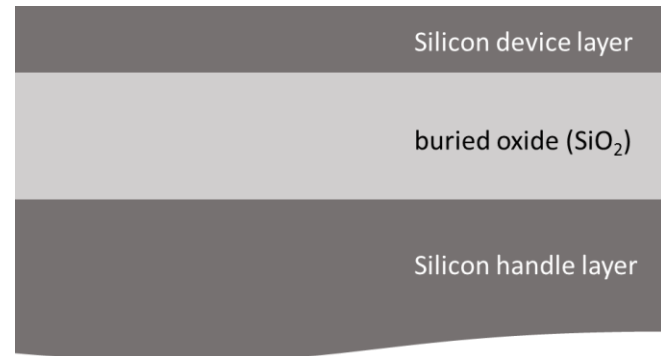
- Highly integrated photonics platform:
  - Filters, lasers, photodetectors, modulators and electronics grown or implemented on the same piece of Silicon

# What is Silicon Photonics?

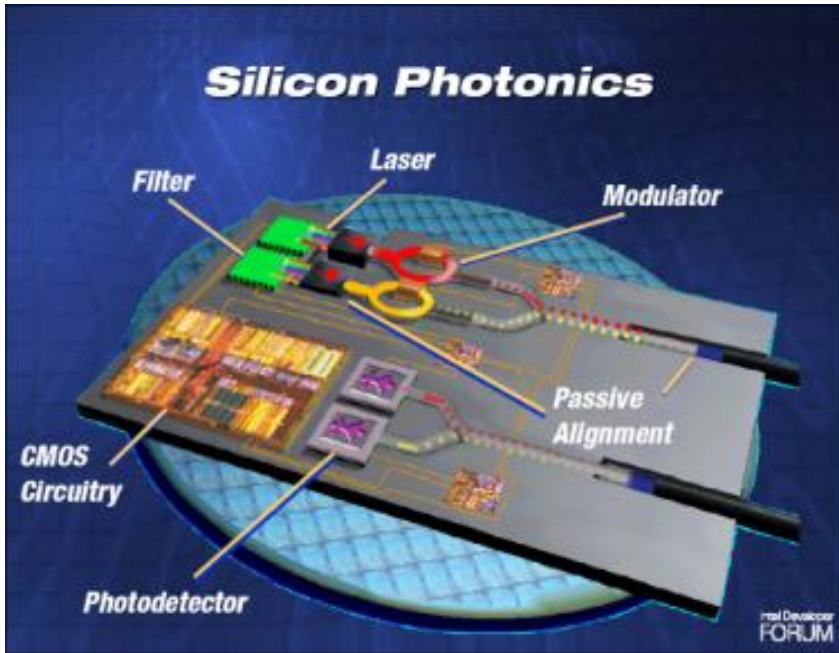


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- Highly integrated photonics platform:
  - Filters, lasers, photodetectors, modulators and electronics grown or implemented on the same piece of Silicon
  - Using Silicon On Insulator (SOI) Wafers

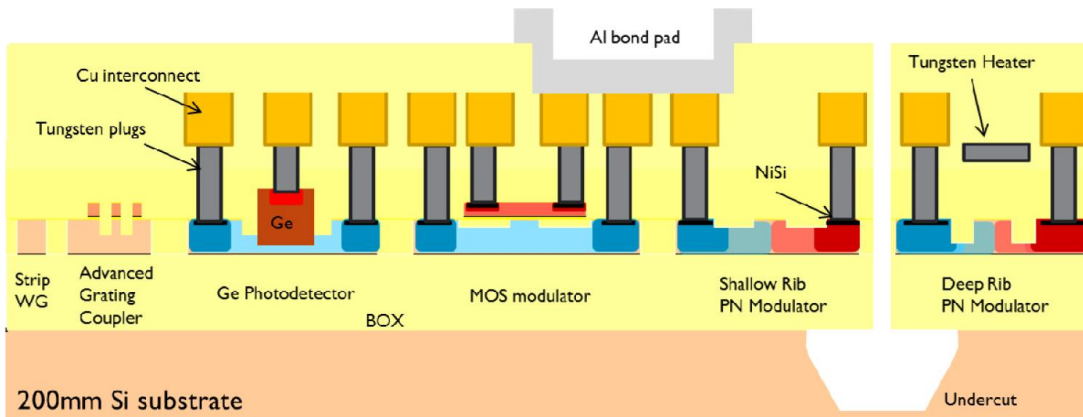
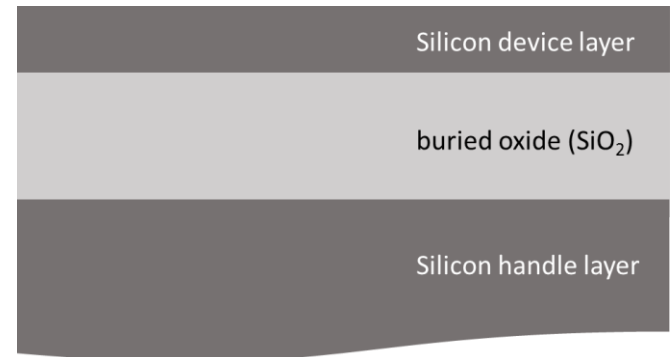


# What is Silicon Photonics?



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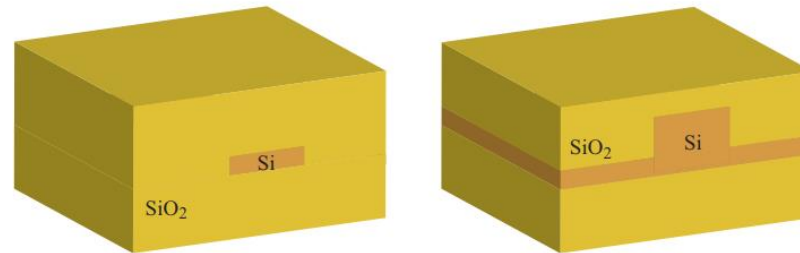
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  - Filters, lasers, photodetectors, modulators and electronics grown or implemented on the same piece of Silicon
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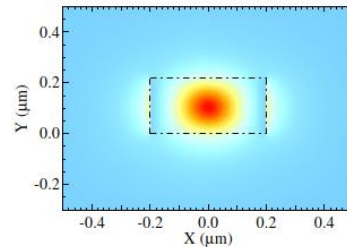
- Well established CMOS processes (patterning and doping of silicon device layer) are used to produce SiPh devices.

# Waveguides – How light travels through the chip

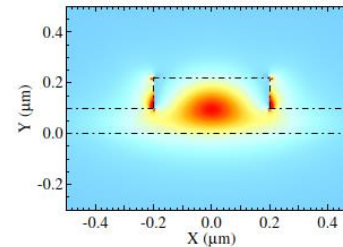
- Structure similar to optical fibers: waveguide core and waveguide cladding
- Fundamental principle: total internal reflection
- More accurate description: optical modes



Optical mode



Channel Waveguide



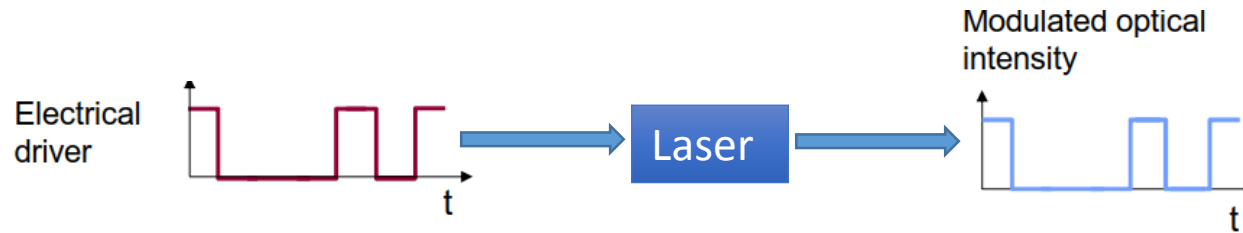
Rib Waveguide

- The deeper the silicon etch the better the confinement
- Depending on the dimensions different optical modes are guided
- Optical communication: preferred to have only the fundamental mode → **single mode**



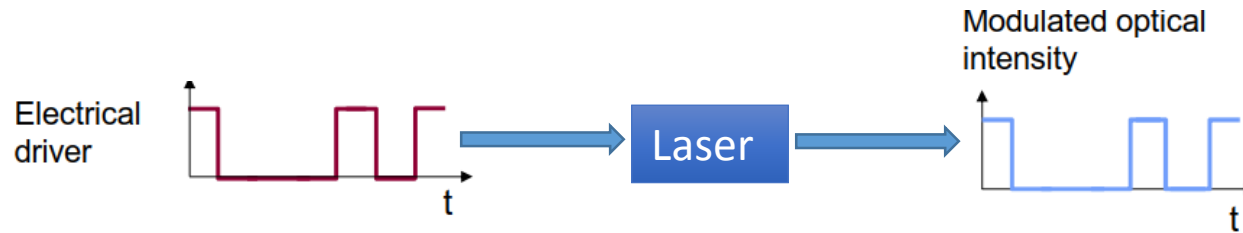
# How is light modulated in Silicon Photonics?

Signal modulation in Laser based Transmitter:

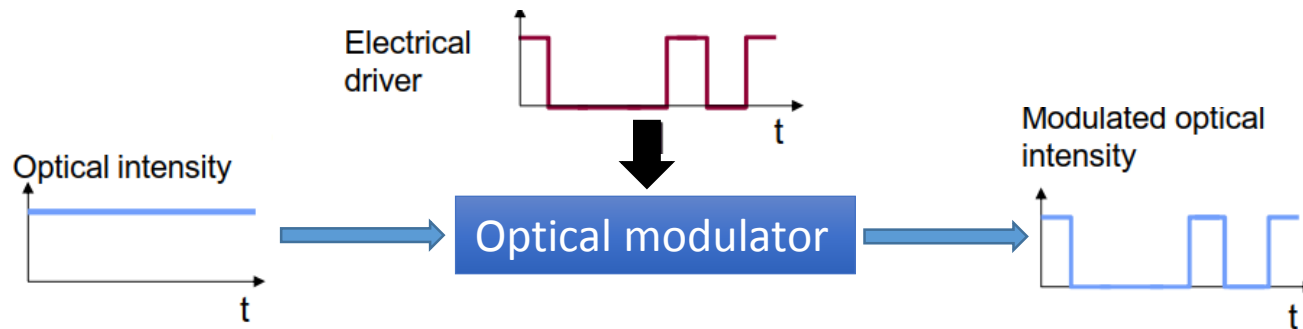


# How is light modulated in Silicon Photonics?

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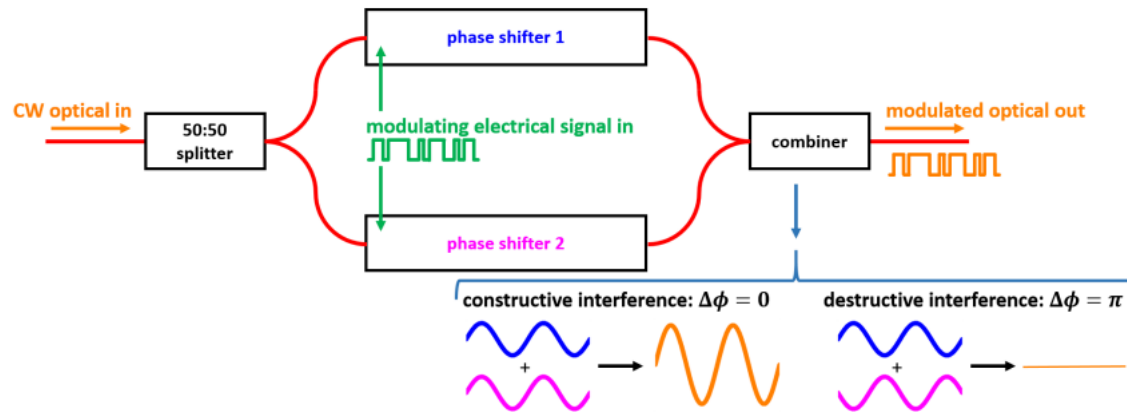


Signal modulation in SiPh based Transmitter:

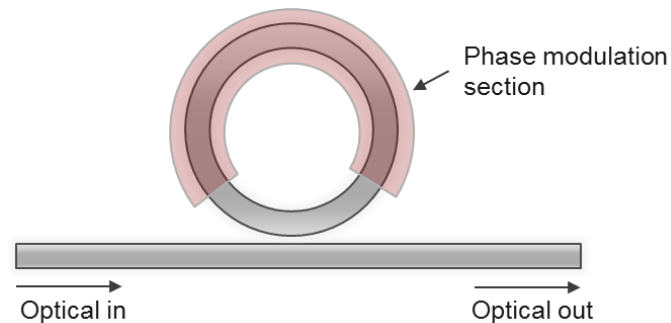


So far we investigated two modulator types

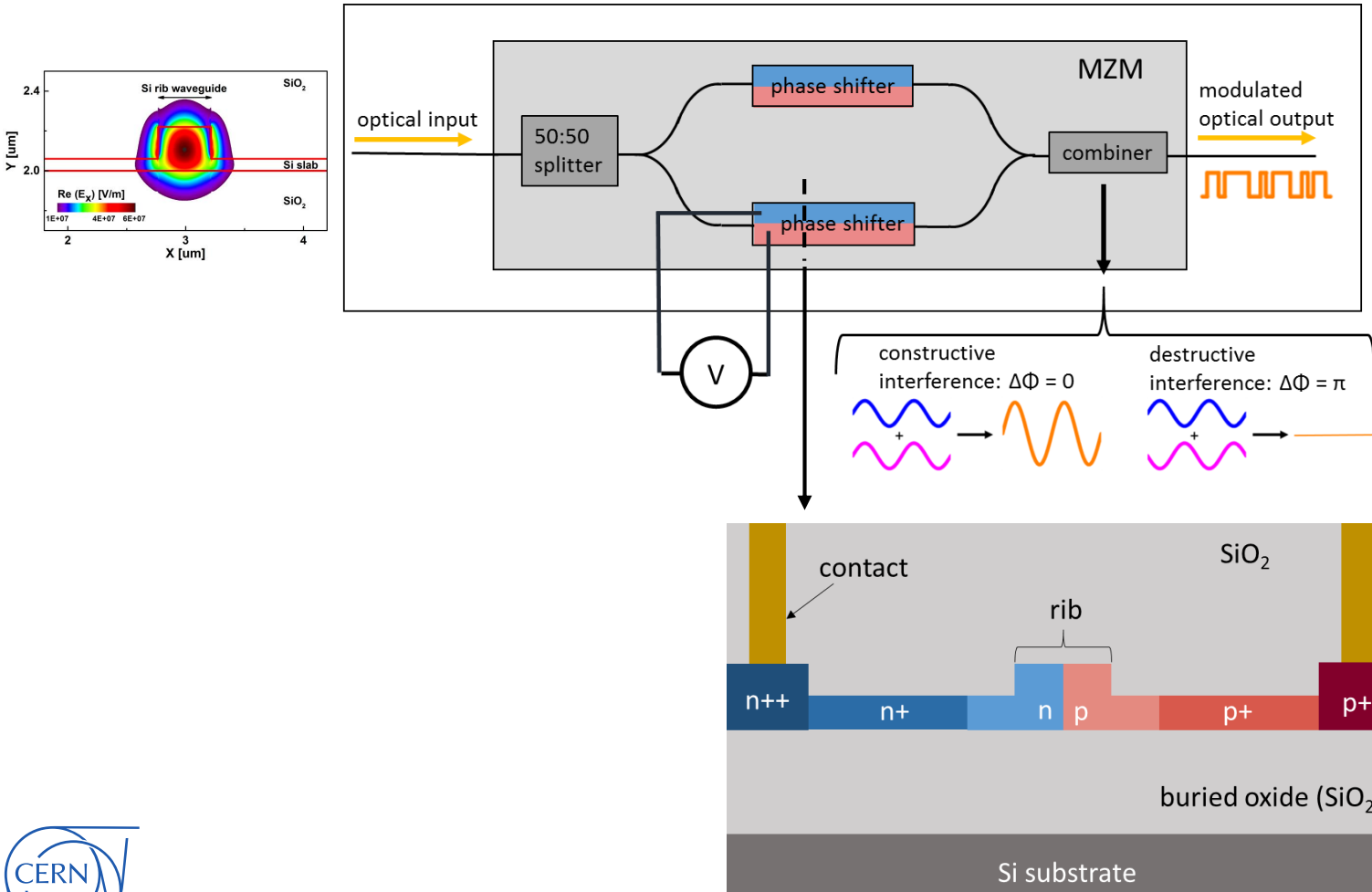
## Mach-Zehnder-Modulator (MZM)



## Ring Modulator (RM)

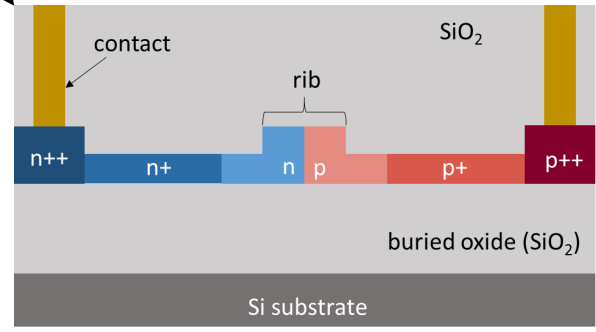
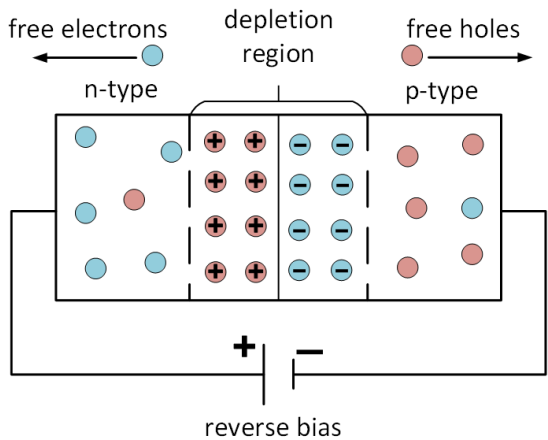
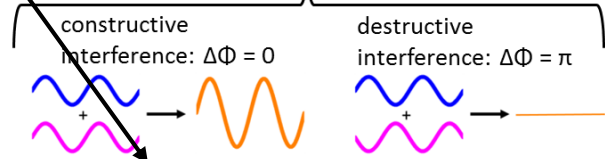
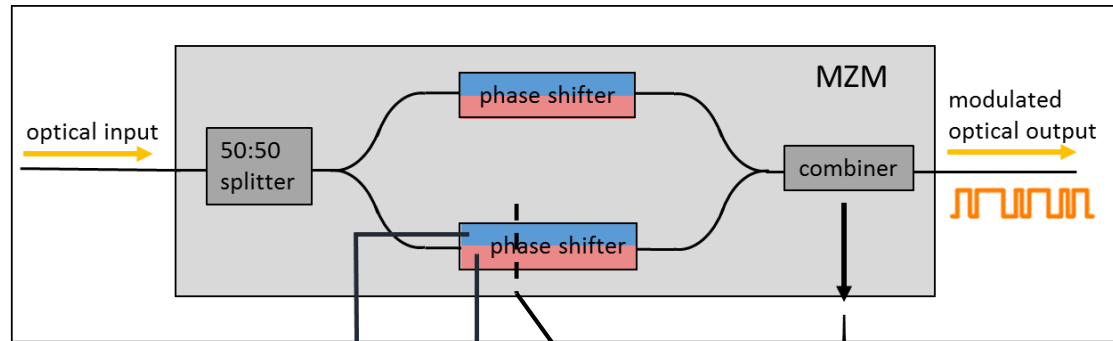


# How does a MZM work?



**Depletion type Phaseshifter:**  
Rib waveguide with pn-junction

# How does a MZM work?



$$\Delta\phi = \frac{2\pi\Delta n_{eff}L}{\lambda}$$

# Silicon photonics a possible alternative for data transmission?

## Advantages:

- Compatibility with CMOS electronics (high density integration)
- small footprint
- higher bit rate
- reduced power consumption

→ This sounds all very good

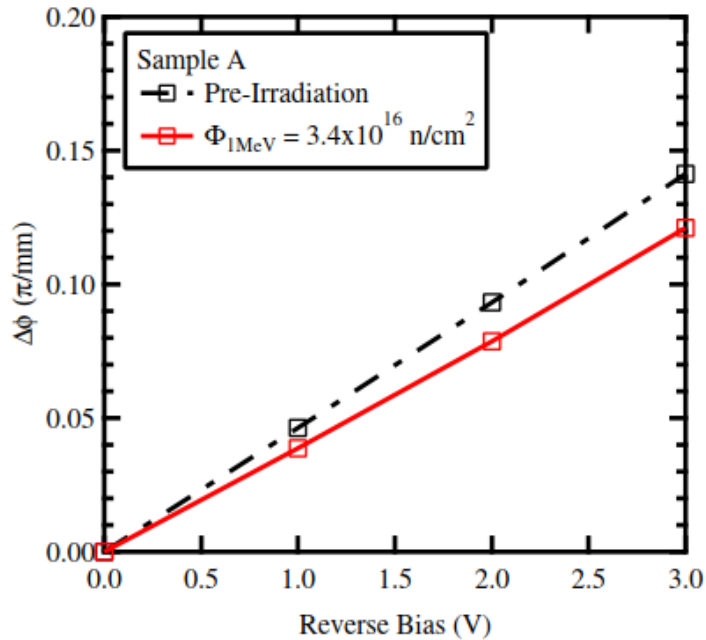
**BUT what about radiation  
hardness???**



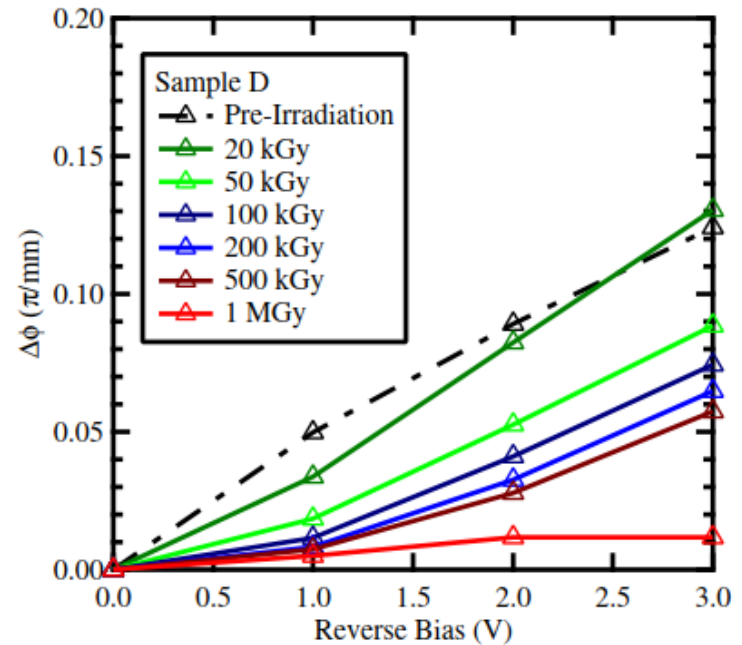
# First irradiation tests performed

At the beginning focus on MZMs as those where the more advanced and promising devices at this time

Displacement damage:



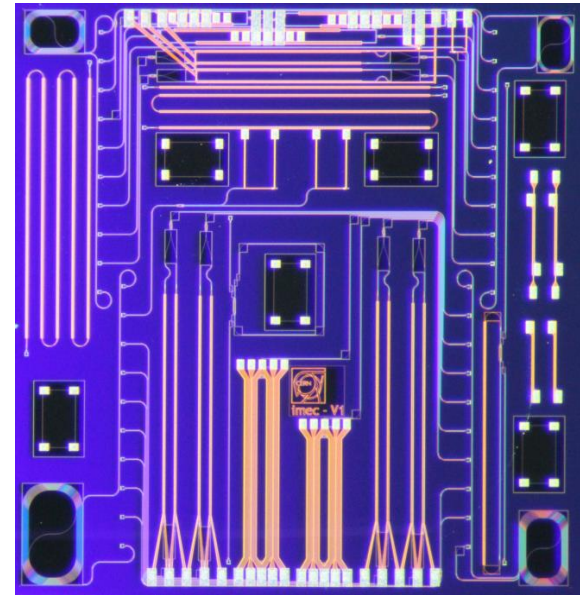
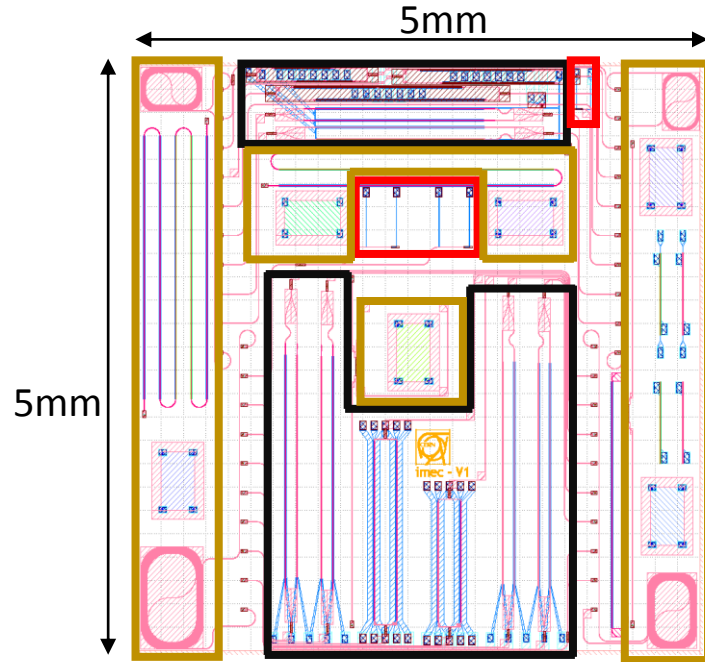
TID:



Very resistant against displacement damage BUT strong degradation due to ionization!!!



# Imec Silicon Photonics test chip



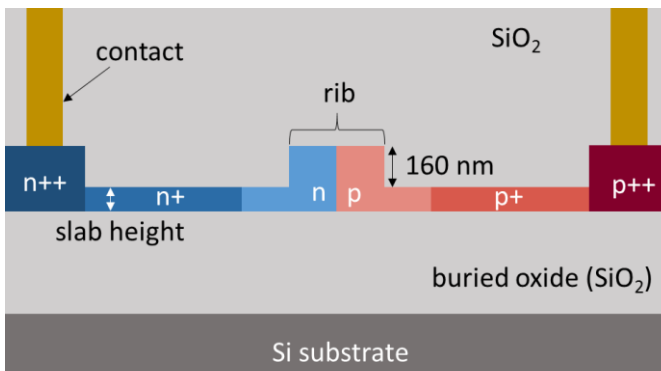
- 12 modulators: MZM building blocks (deep etch with travelling wave electrodes), MZM customized designs (deep and shallow etch without travelling wave electrodes) and a RM building block
- 3 germanium on silicon photo diodes
- Various passive test components
- Produced on 200 mm SOI wafers in the IMEC ISIPP25G technology (ePIXfab MPW)



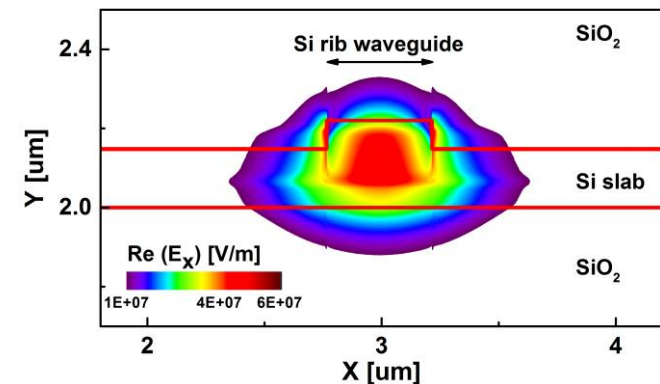
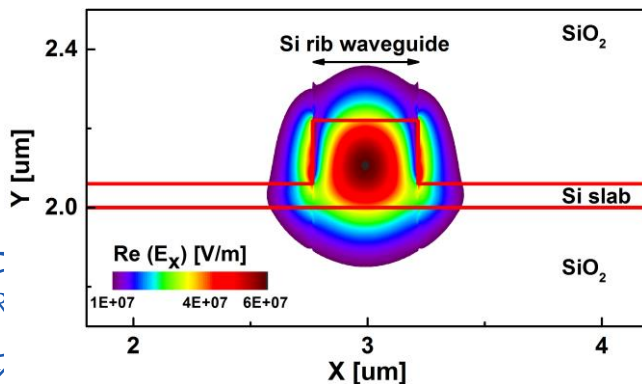
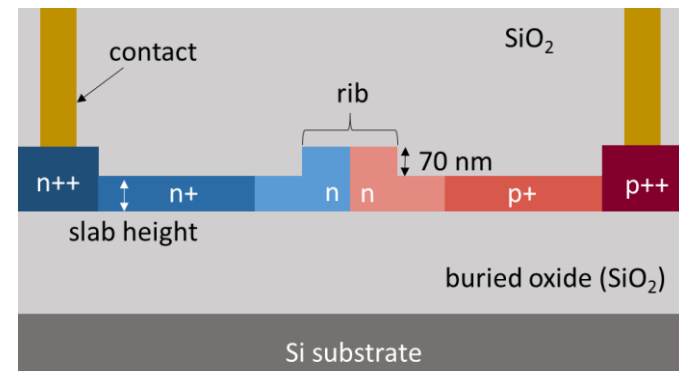
# Improvement of radiation hardness by design

To experimentally test the influence of design variations **2 customized designs** are produced in **2 doping concentration** flavors and are compared

deep etch



shallow etch



# X-ray irradiation tests of MZMs

## 1<sup>st</sup> Influence of Design:

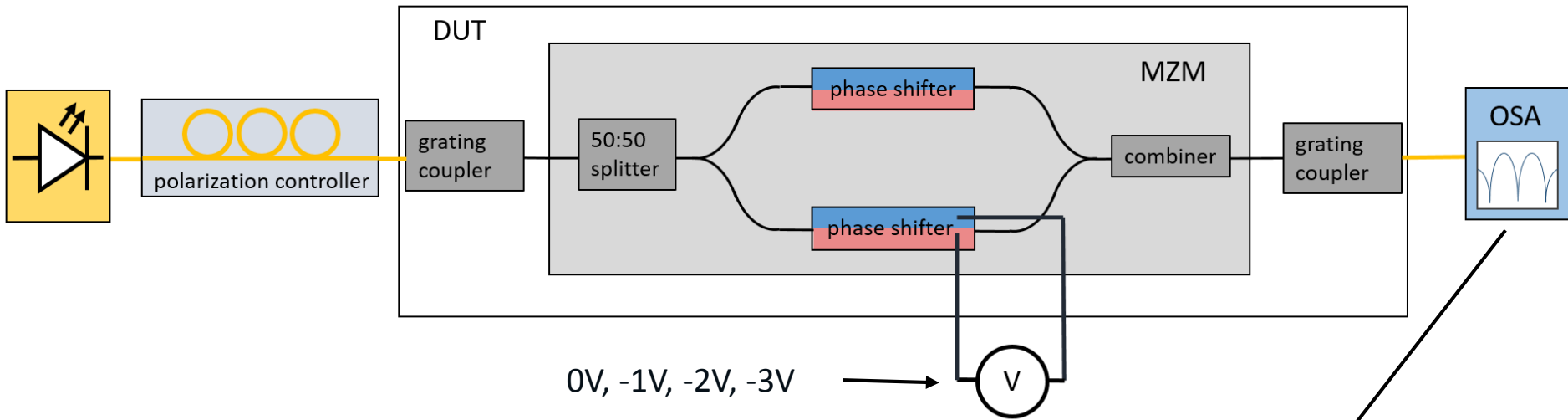
- Slab height – etch depth
- Doping concentration

## 2<sup>nd</sup> Influence of environment and measurement parameters:

- Temperature dependence
- Bias dependence
- Post-irradiation and annealing

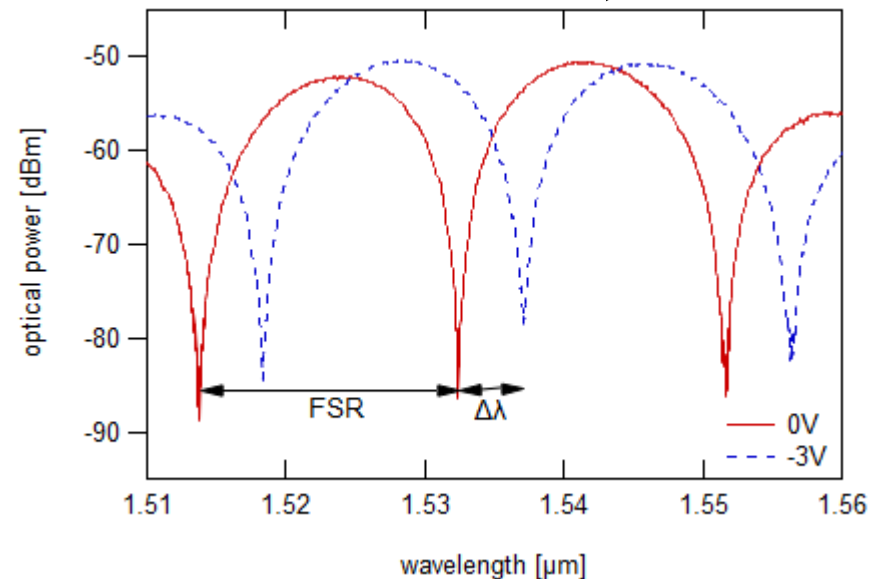


# Testing of MZMs – Static phase shift

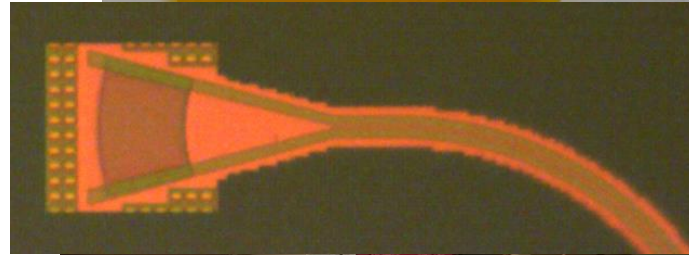
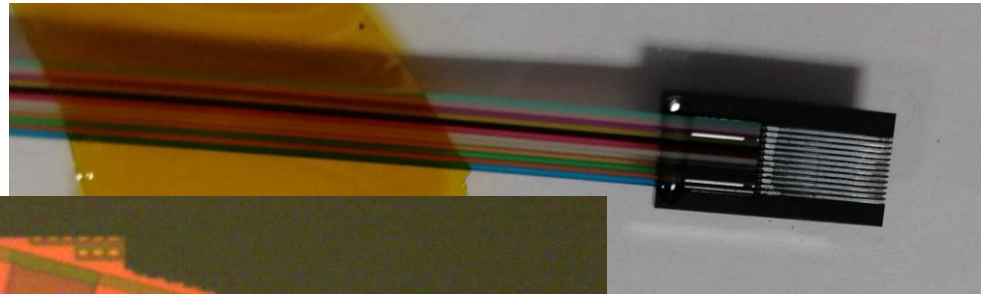
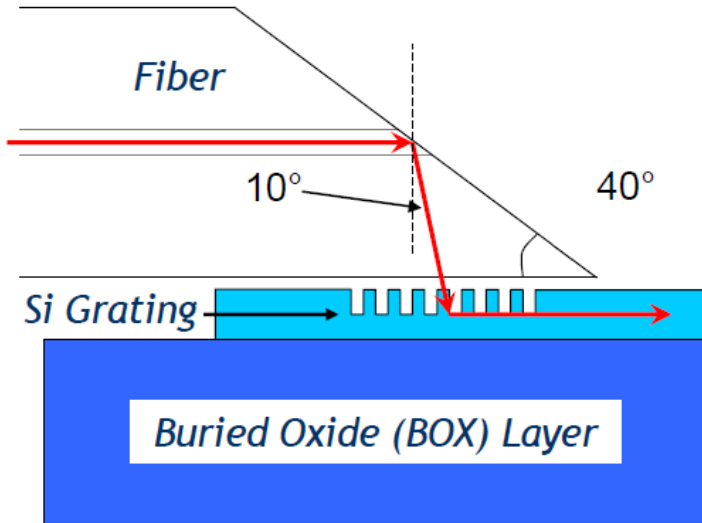


- Fitting spectra and extraction of FSR and  $\Delta\lambda$
- Calculating  $\Delta\Phi$  for -1V, -2V and -3V reverse voltage

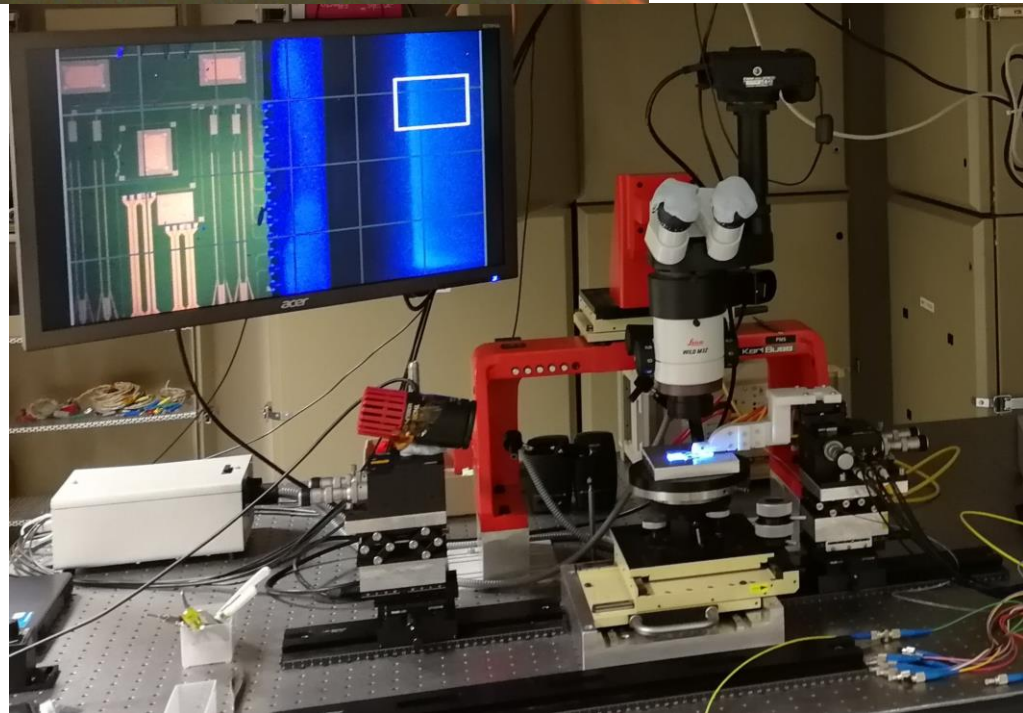
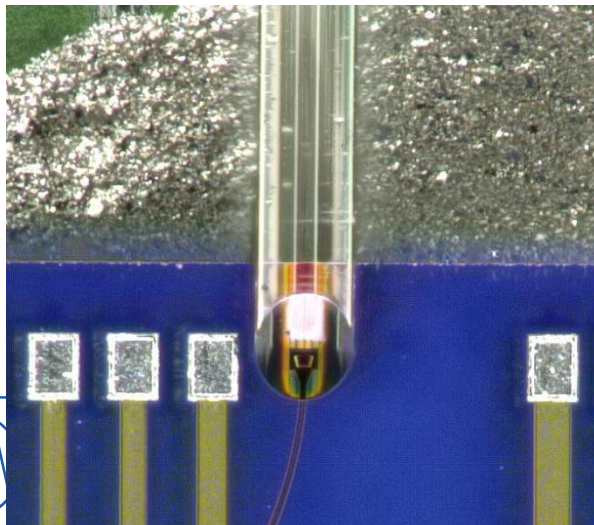
$$\Delta\Phi = \frac{2\Delta\lambda}{FSR \cdot L}$$



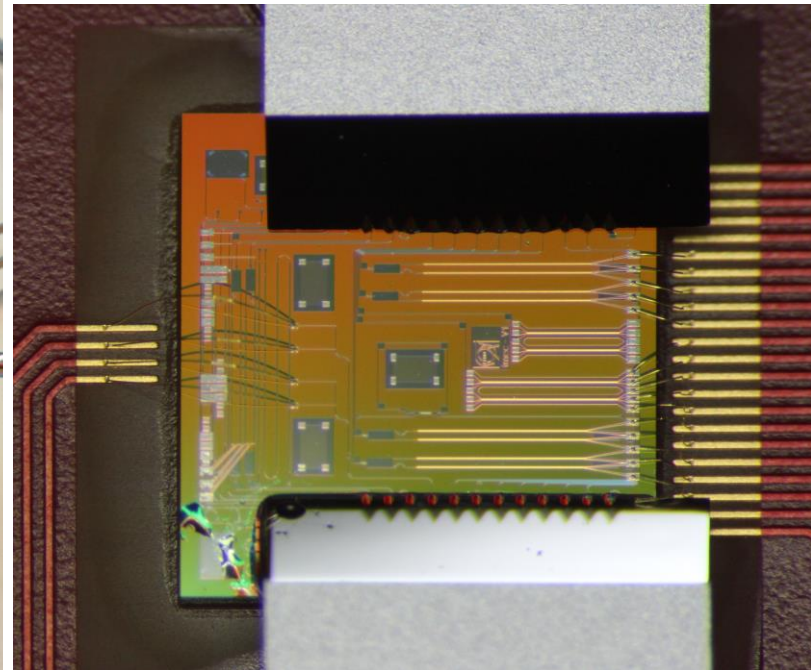
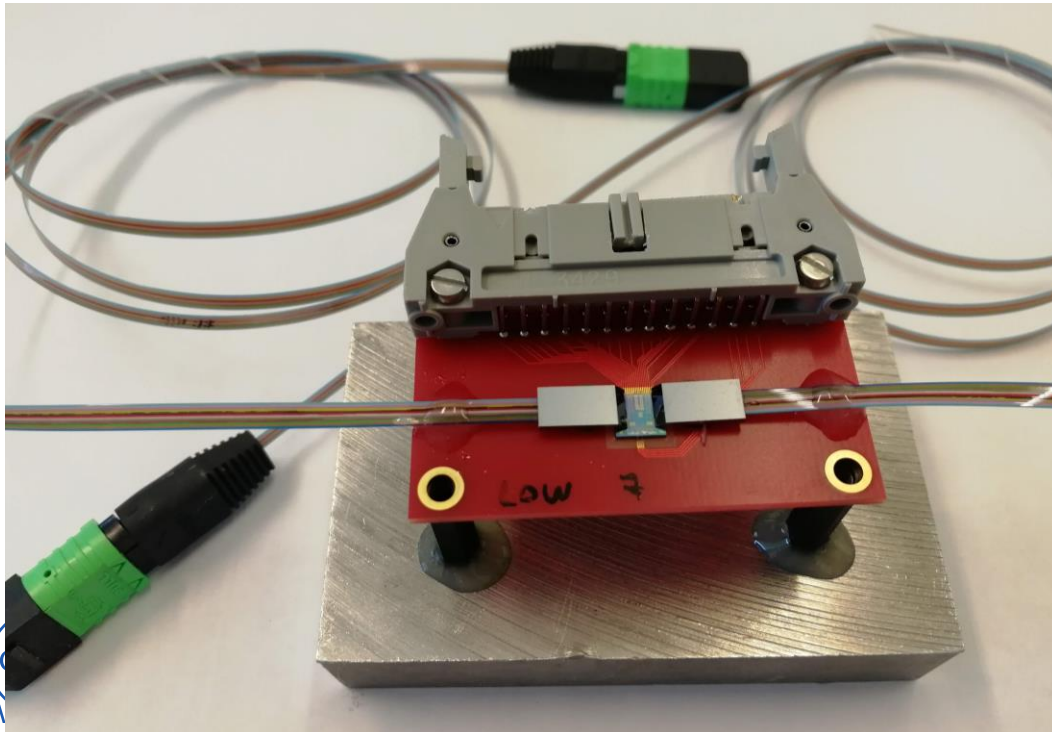
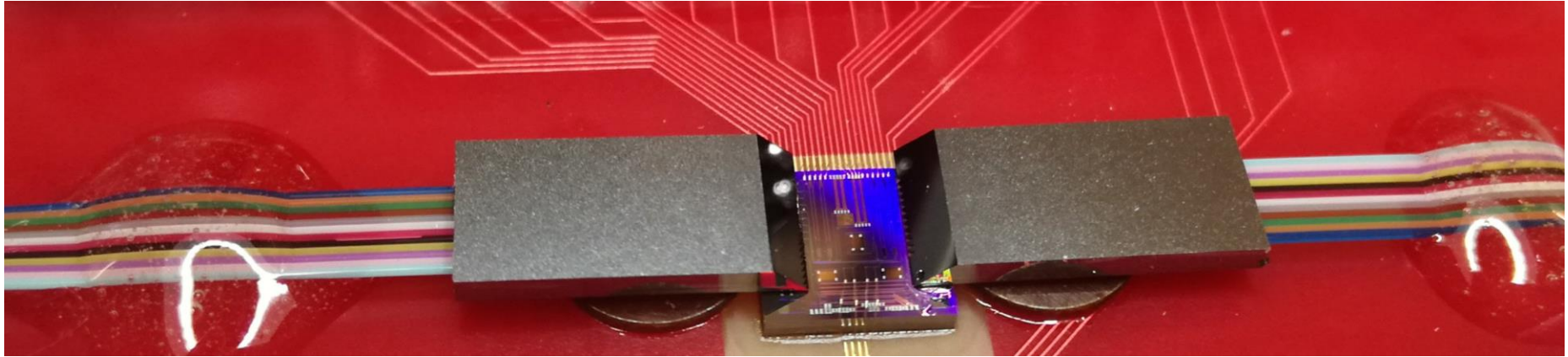
# Planar fiber coupling - Pigtailed



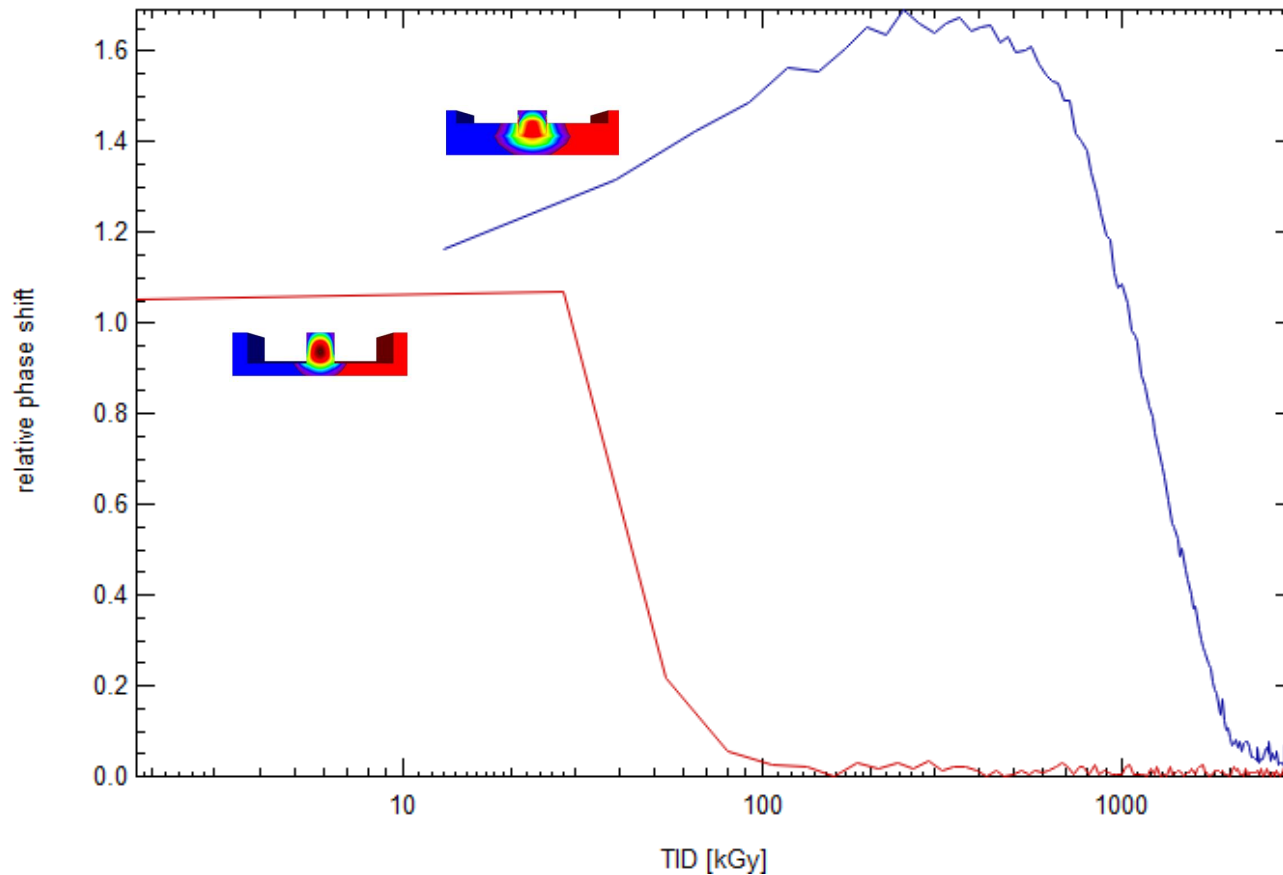
B. Snyder et al, IEEE TRANSACTIONS ON COMPONENTS, PACKAGING AND MANUFACTURING TECHNOLOGY, VOL. 3, NO. 6, JUNE 2013



# Assembled chip

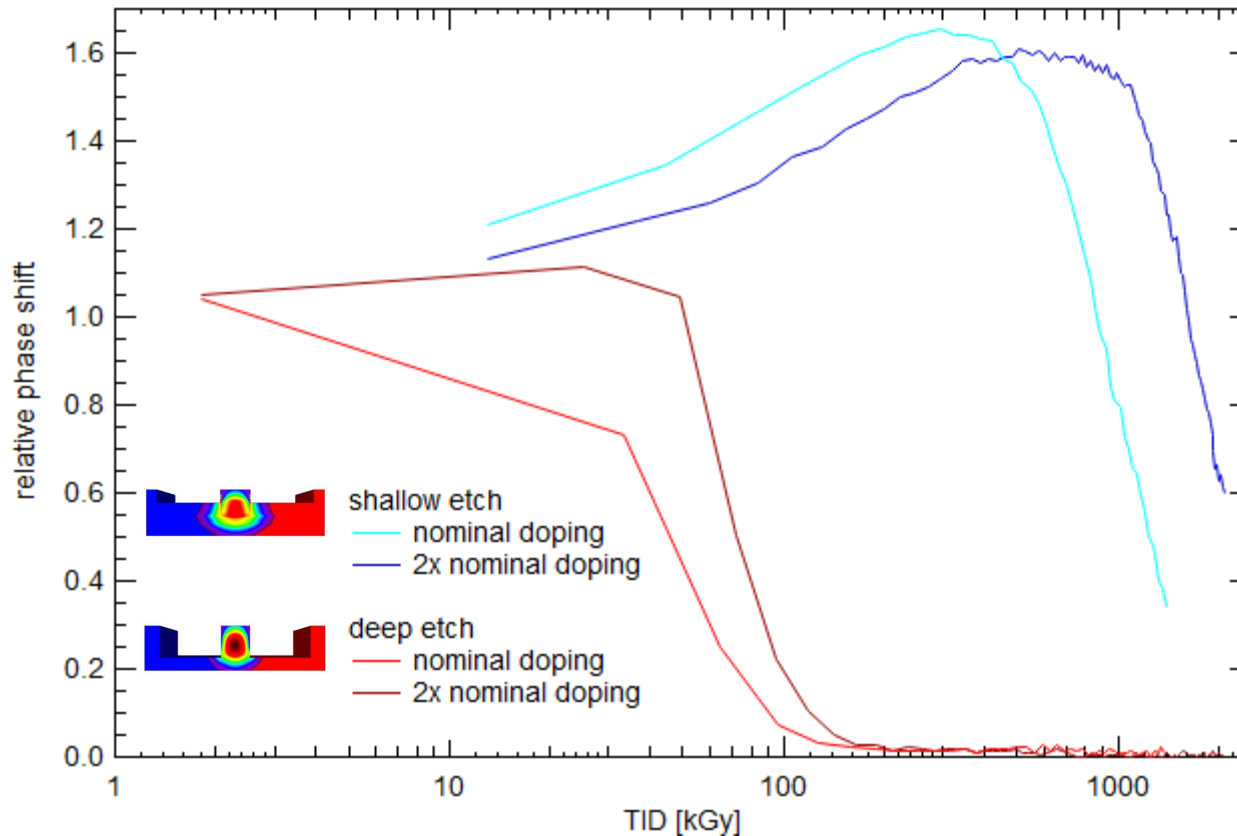


# X-ray test - Deep etch vs. shallow etch



- ☺ The shallower the better the radiation resistance
- ☹ The shallower the lower the mode confinement → lower modulation efficiency and higher losses

# X-ray test - High doping vs. low doping

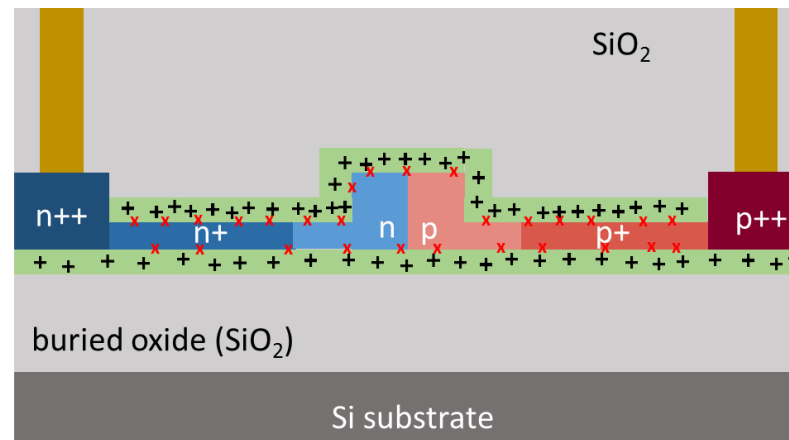


- ☺ The higher the better the radiation resistance (slab region)
- ☺ The higher the bigger the phase shift (rib)
- ☹ The higher the bigger the losses in the phase shifter (rib)

# Effect of ionizing radiation on Silicon Photonics

Ionizing radiation creates e-h pairs in the rather thick oxide. This leads to:

- A. Hole trapping in deep traps in the oxide close to the Si/SiO<sub>2</sub> interface
- B. Buildup of acceptor/donor interface traps
- C. Hydrogenation – Passivation of dopants

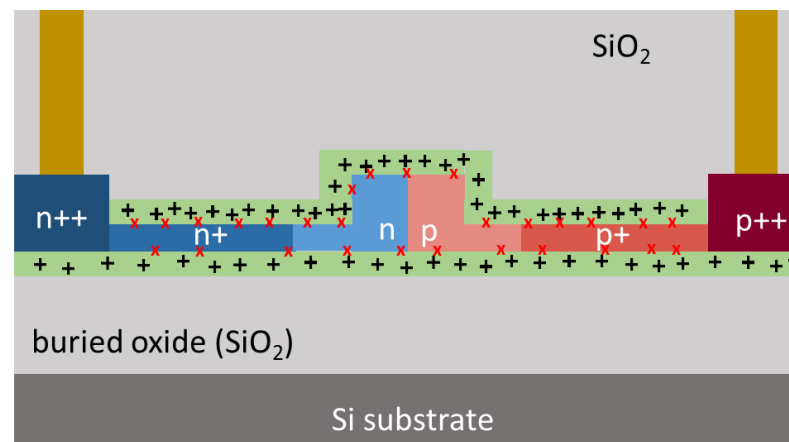




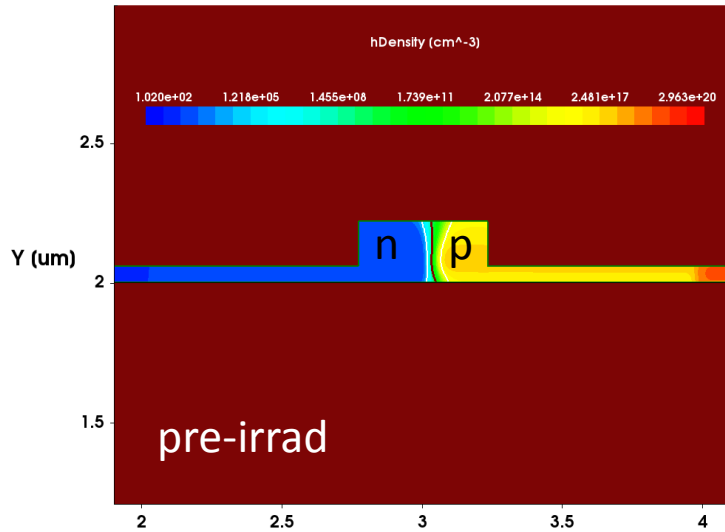
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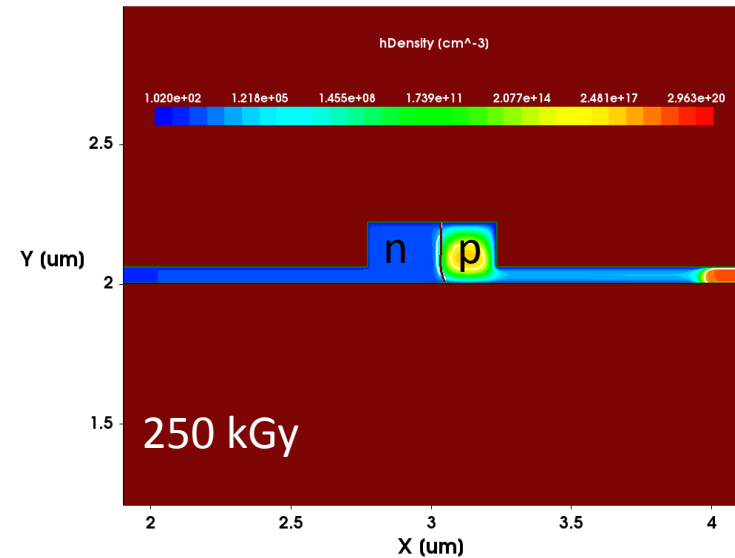
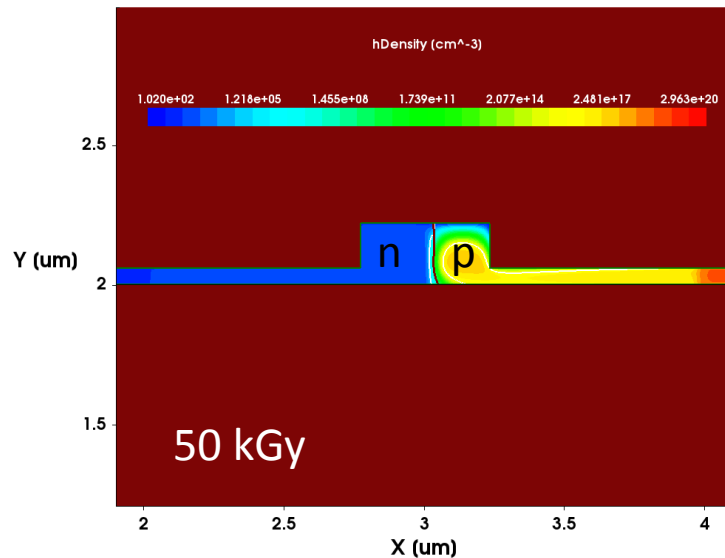
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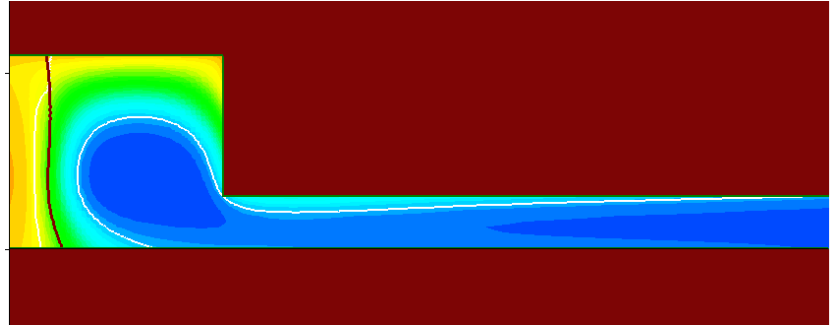
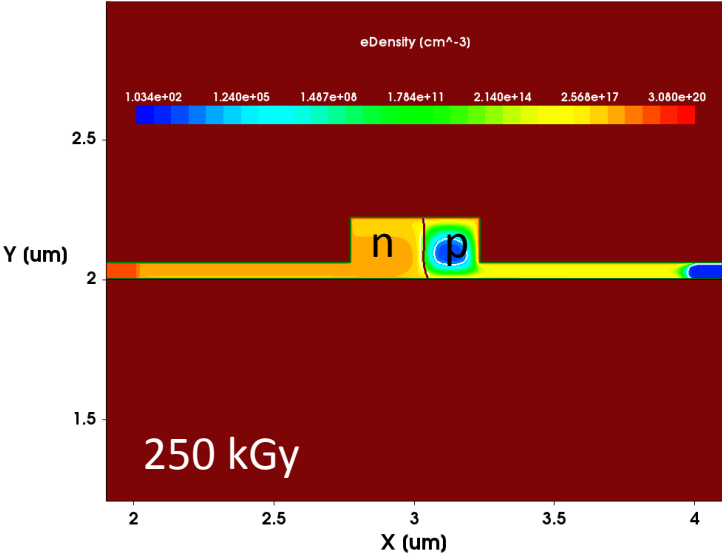
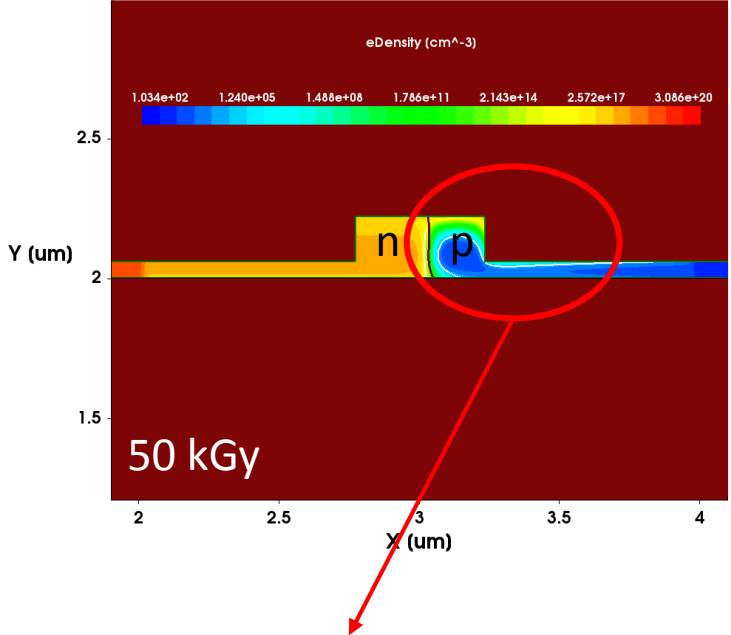
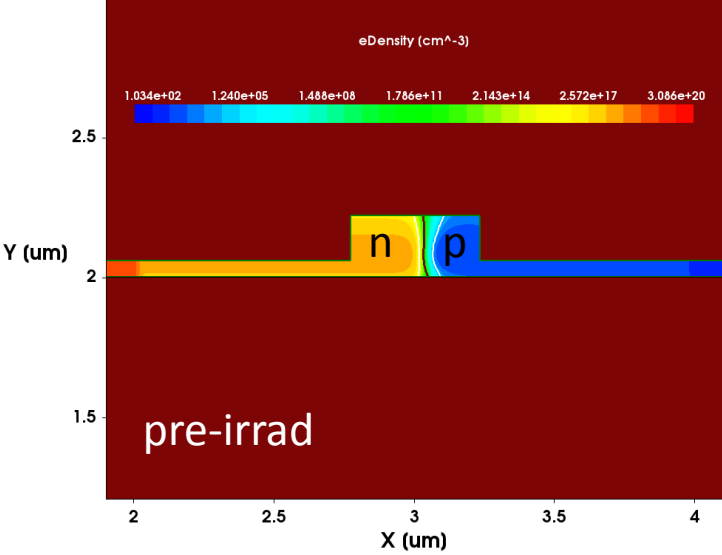
# Simulation of ionizing radiation effects – hole density



With increasing irradiation the concentration of positive charge close to the interface increases

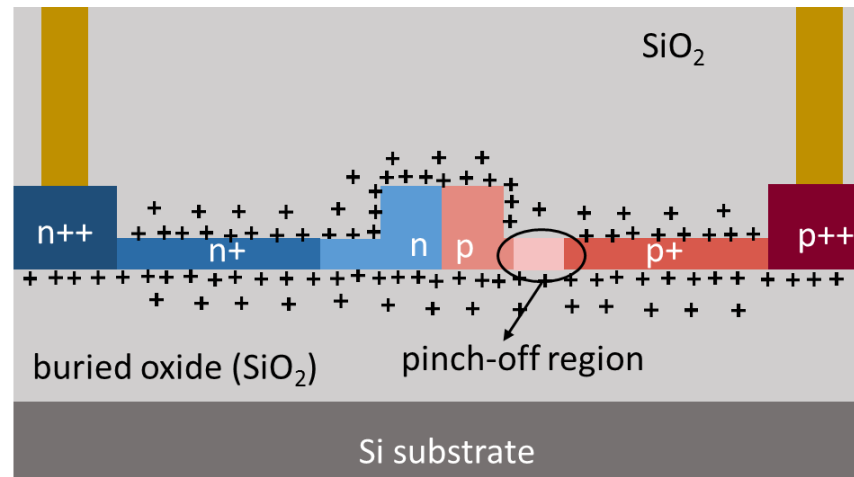


# Simulation of radiation effects – electron density



# What did we learn from the simulation?

- The positive charges trapped close to the interface lead to an accumulation of electrons and removal of holes on the p-side
- Pinch-off in slab region → no modulation possible anymore



→ Both; increasing the doping and the slab height leads to a delay of the pinch-off effect

# X-ray irradiation tests of MZMs

## 1<sup>st</sup> Influence of Design:

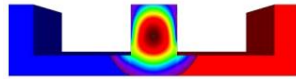
- Slab height – etch depth
- Doping concentration

## 2<sup>nd</sup> Influence of environment and measurement parameters:

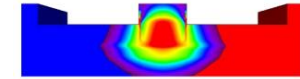
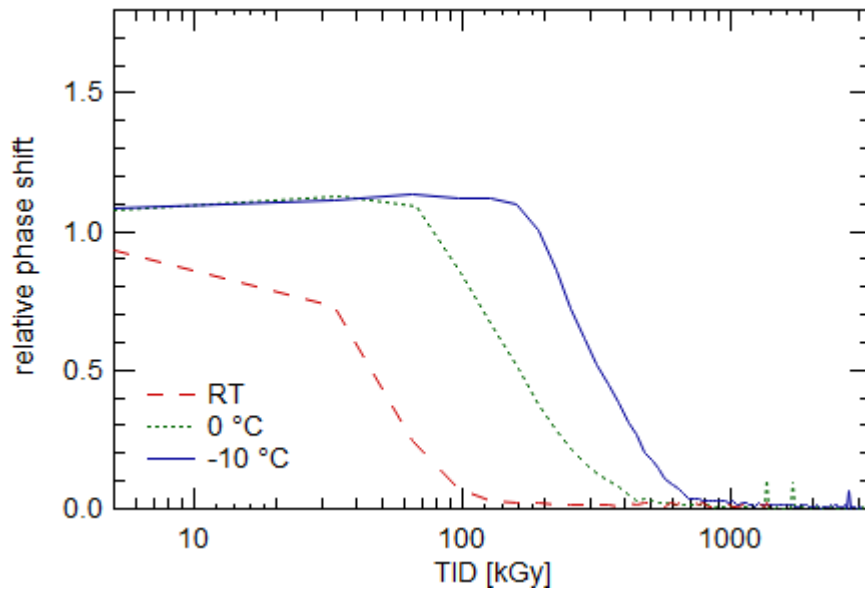
- Temperature dependence
- Bias dependence
- Post-irradiation and annealing



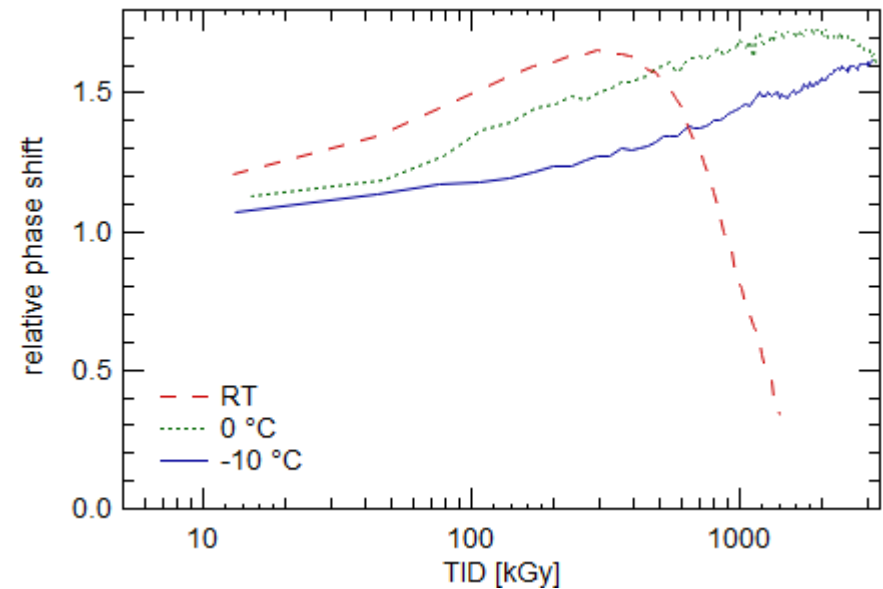
# X-ray test - Temperature dependence



deep etch



shallow etch



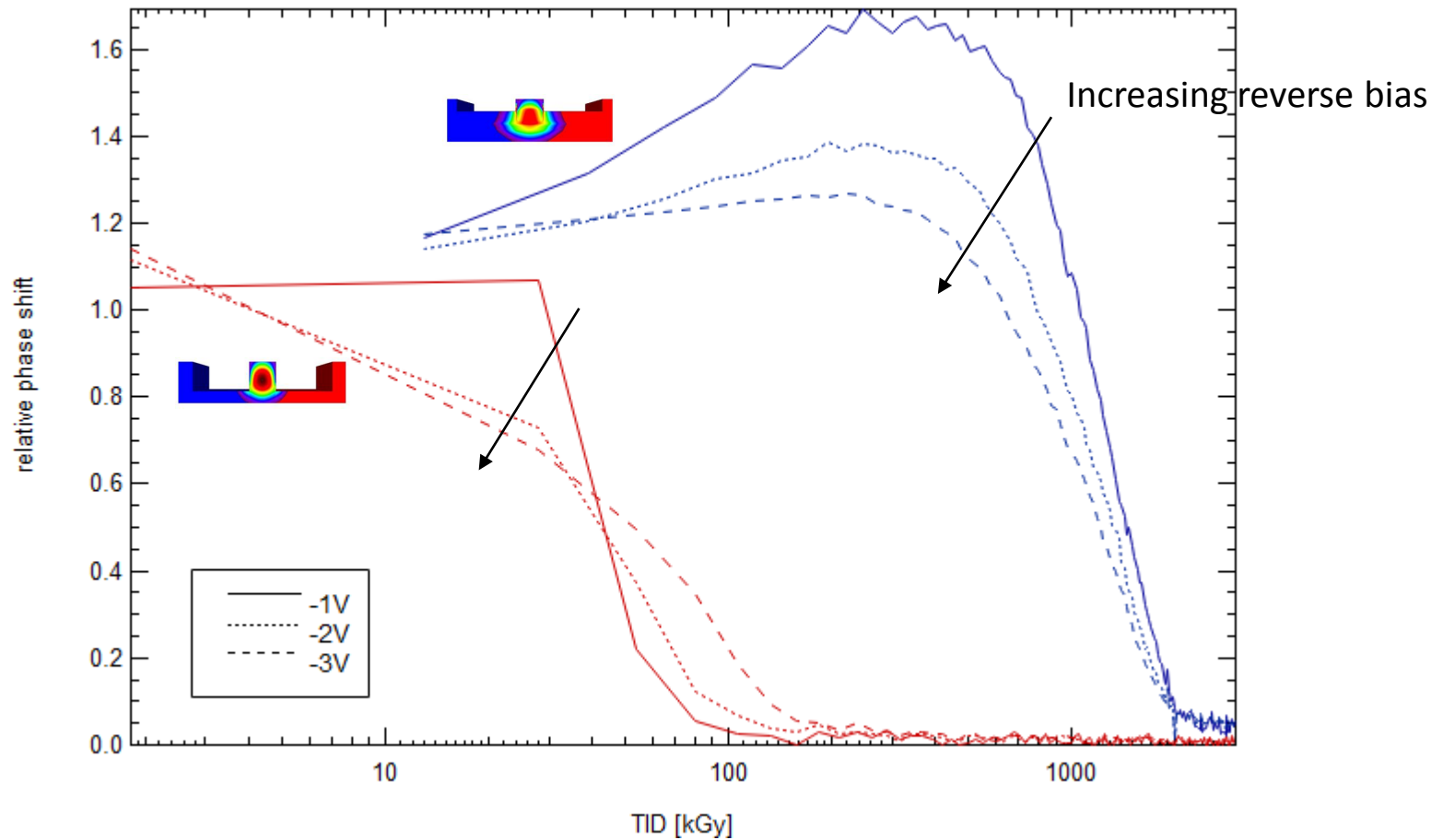
☺ The lower the temperature the higher the radiation tolerance for shallow and deep etch devices

Reason: Reduction of hole mobility → lower rate at which deep traps are filled and interface traps are built up

# Effect of biasing during irradiation

- Reverse bias applied during irradiation → decreased radiation resistance
- Forward bias applied after irradiation → device recovery (annealing)

# X-ray test - Bias dependence



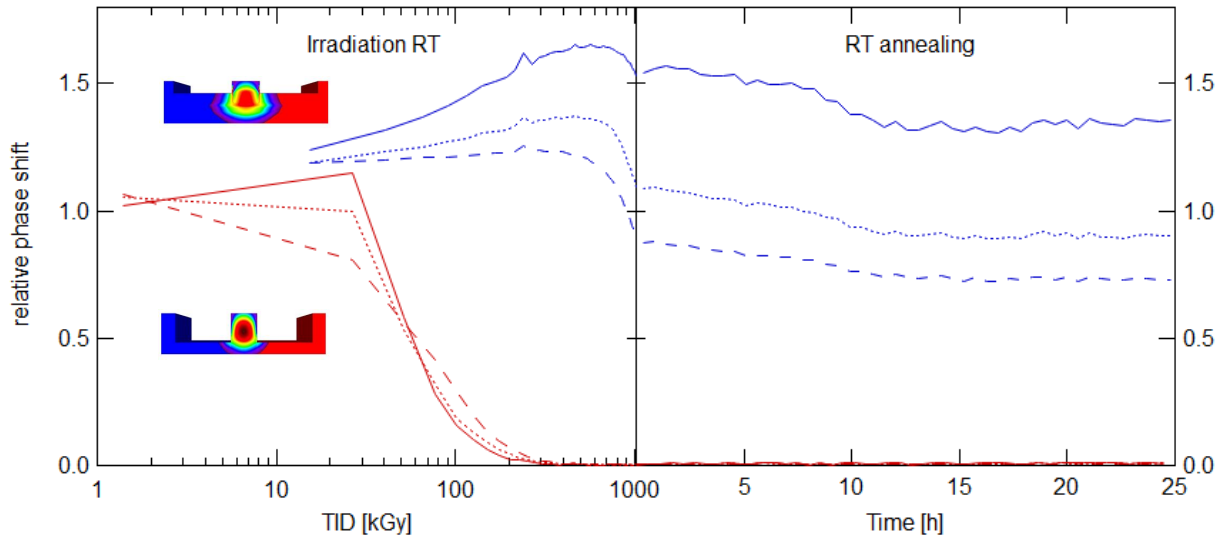
The higher the bias the higher the electric field → holes move faster through the oxide towards the interface



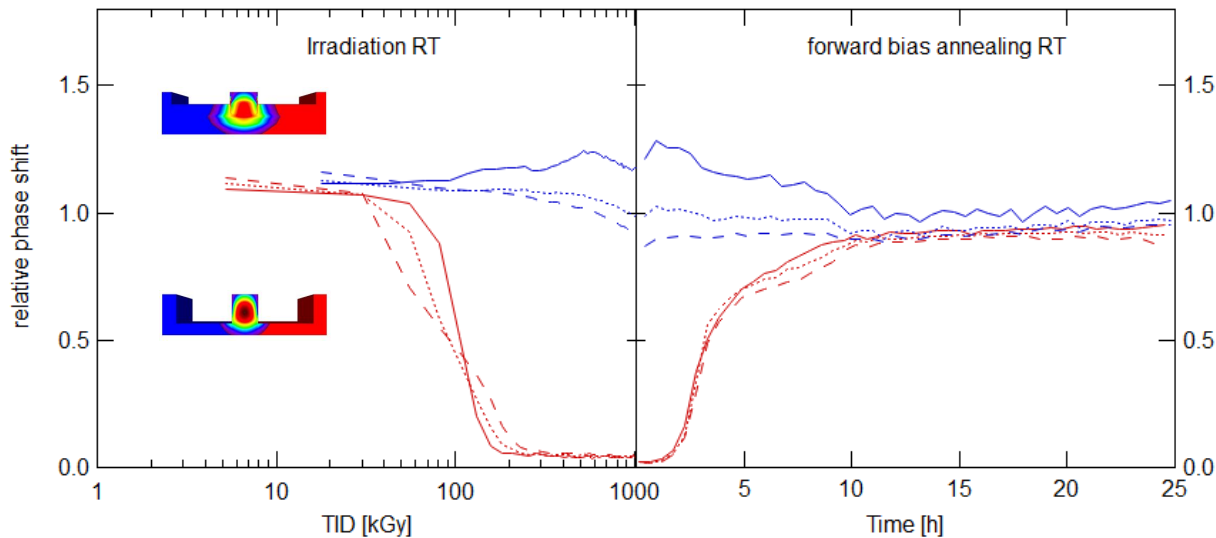
# Effect of biasing during irradiation

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# Annealing due to forward biasing



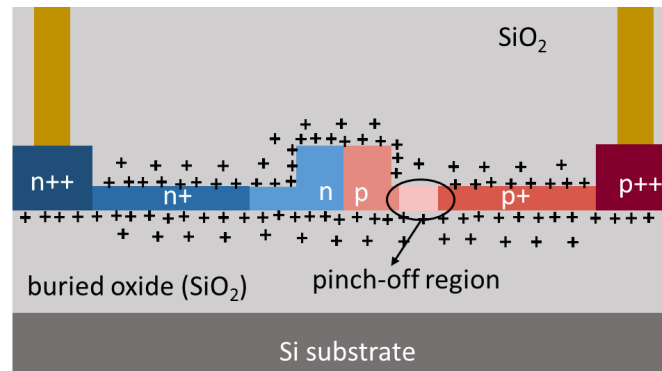
no forward bias  
at all (no IV)



2 mA forward  
current for 1 min  
every cycle

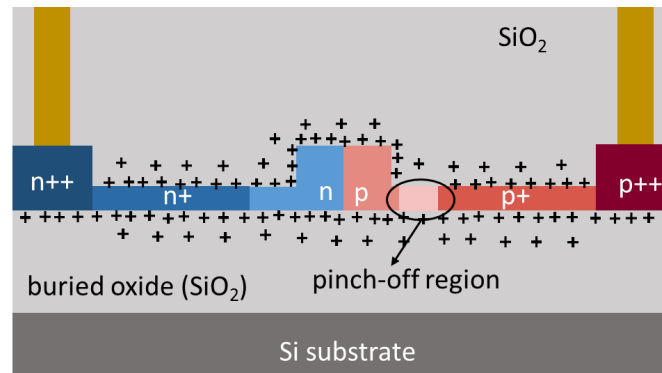
# Annealing due to forward biasing

What's the reason for the forward bias annealing???

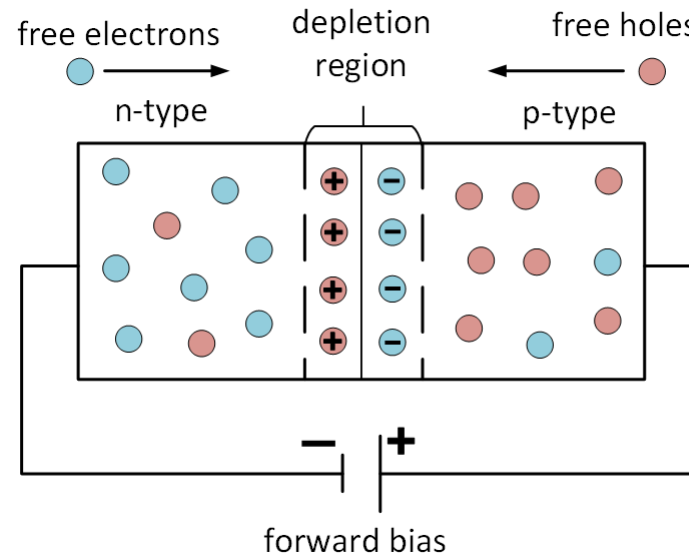


# Annealing due to forward biasing

What's the reason for the forward bias annealing???



In forward bias electrons are pushed towards the p-side → they can tunnel into the oxide and eliminate trapped holes



# Effectiveness of annealing

To evaluate the effectiveness of the annealing re-irradiation tests were performed

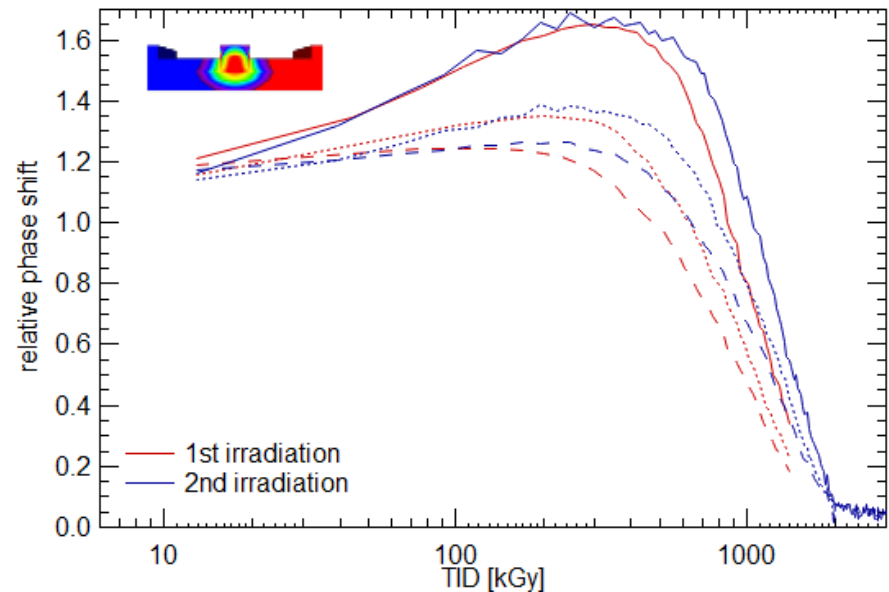
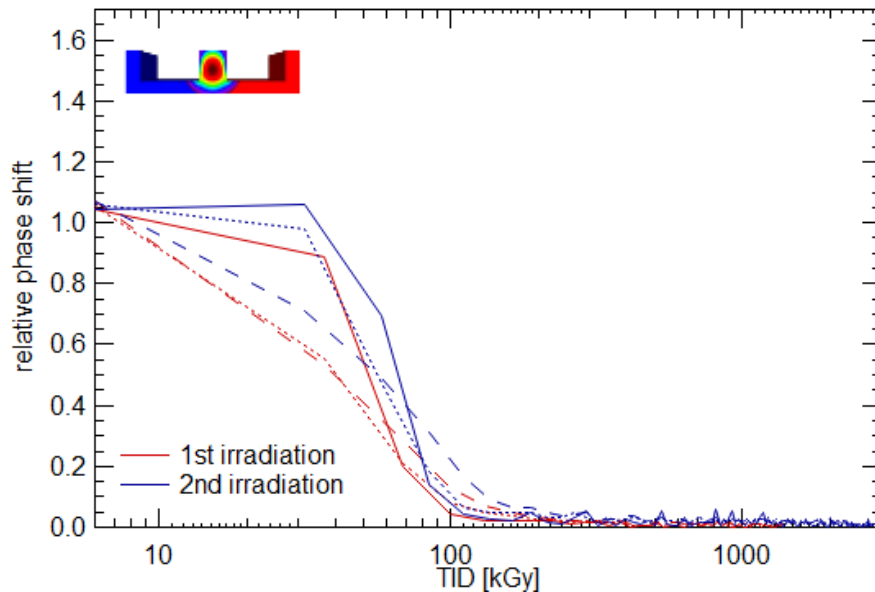
A. 1<sup>st</sup> irradiation up to device failure

B. Annealing: 10 mA forward current for 24 hrs followed by -3 V reverse bias for 24 hrs

C. 2<sup>nd</sup> irradiation at the same conditions as 1<sup>st</sup> irradiation

# Annealing and Re-irradiation

After 1<sup>st</sup> irradiation annealing with 10 mA forward for 24 hrs followed by 2<sup>nd</sup> irradiation → same irradiation resistance in both irradiation runs → **full recovery of the device!!!**

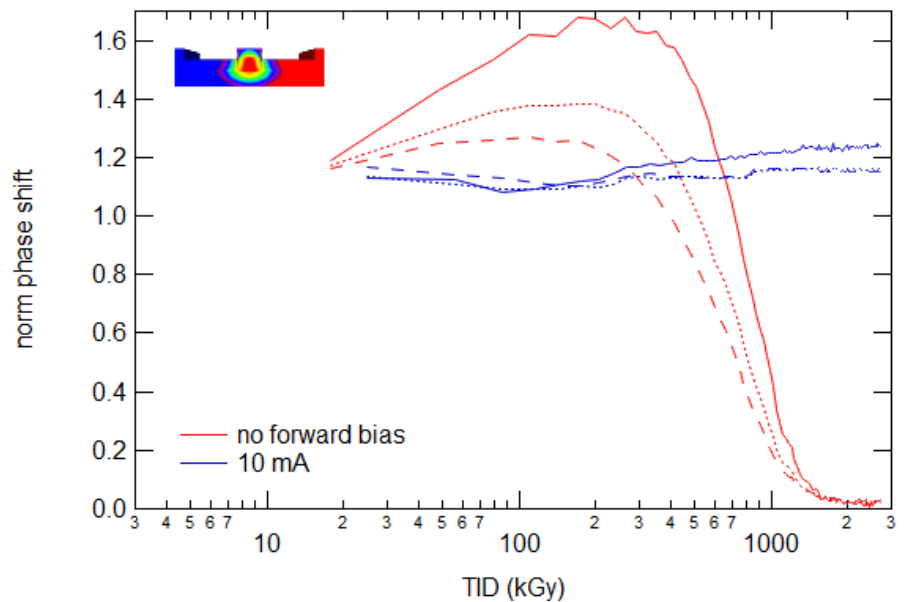
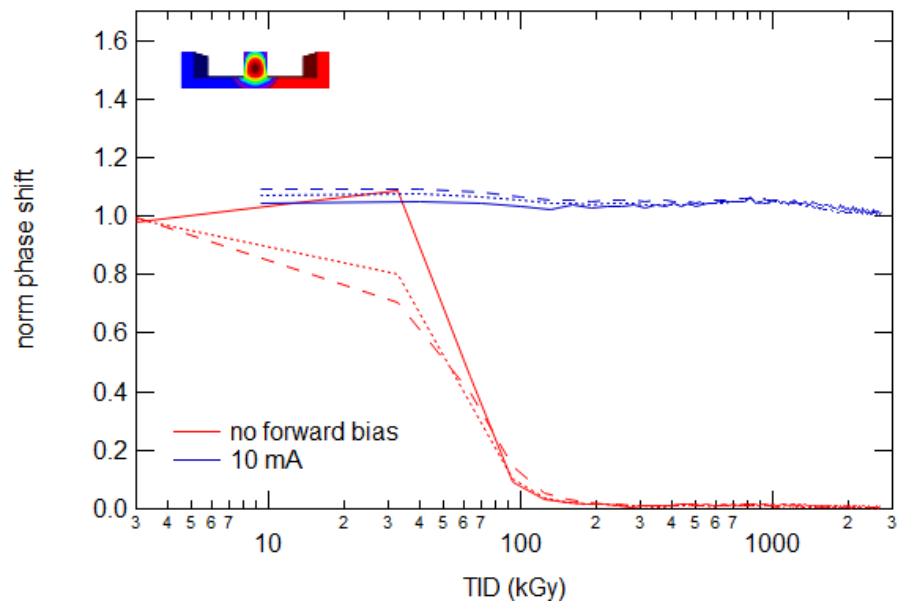


# Forward bias annealing

- The next question is; is it possible to compensate the irradiation effects already during irradiation with a high enough forward bias???
- 2 mA for 1 min every measurement cycle only showed little influence during irradiation
- New test with 10 mA for 1 min every measurement cycle

# Forward bias annealing

10 mA forward for 1 minute in every measurement



No degradation up to 3 MGy → compensation of irradiation effect during irradiation



# Conclusion of these results

- Forward bias could be applied in phases where operation of HEP experiments are paused eg. shutdowns, technical stops, interfills
- With the possibility of recovery or even compensation of the radiation effect the necessity of designing customized devices together with their drawbacks in functionality is eliminated
- Standard, performance optimized devices offered by foundries could be used

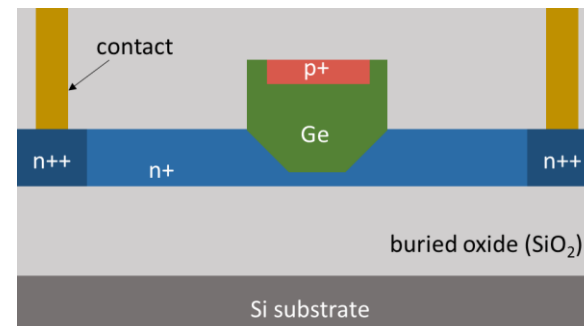
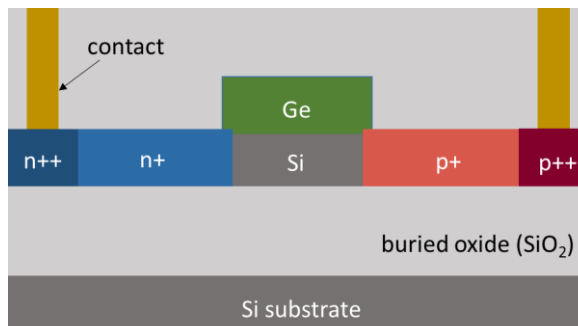


# Irradiation tests of SiGe Photodiodes

- To ensure radiation resistance of a system photodiodes have to be tested as well
- We don't have a lot of information about the SiGe photodiodes on our test chip

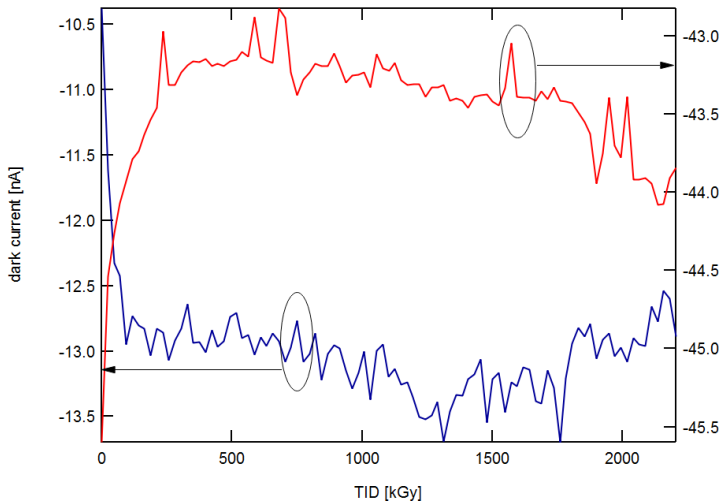
→ Testing of a “black box”

→ As it is most likely a PIN diode we were worried about the intrinsic region in the Germanium

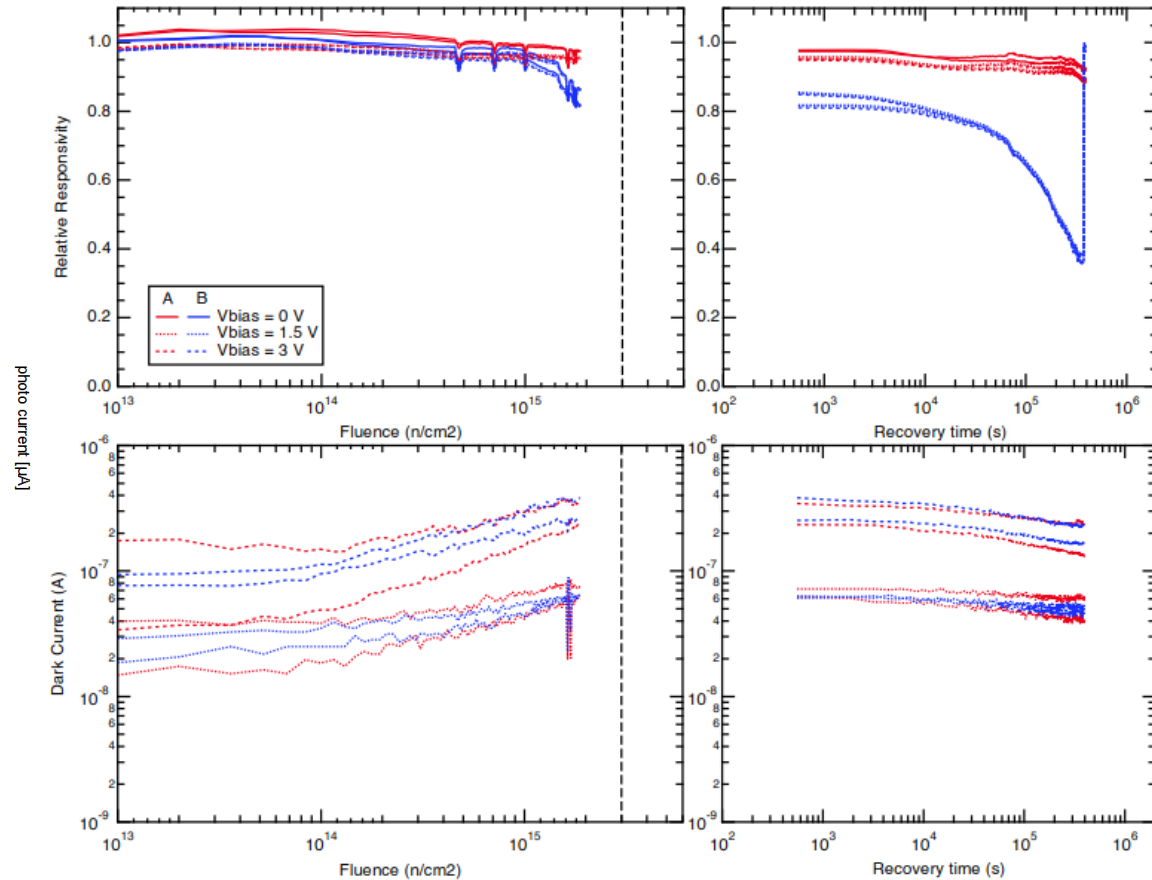


# Irradiation tests of SiGe Photodiodes

## Ionizing Radiation:

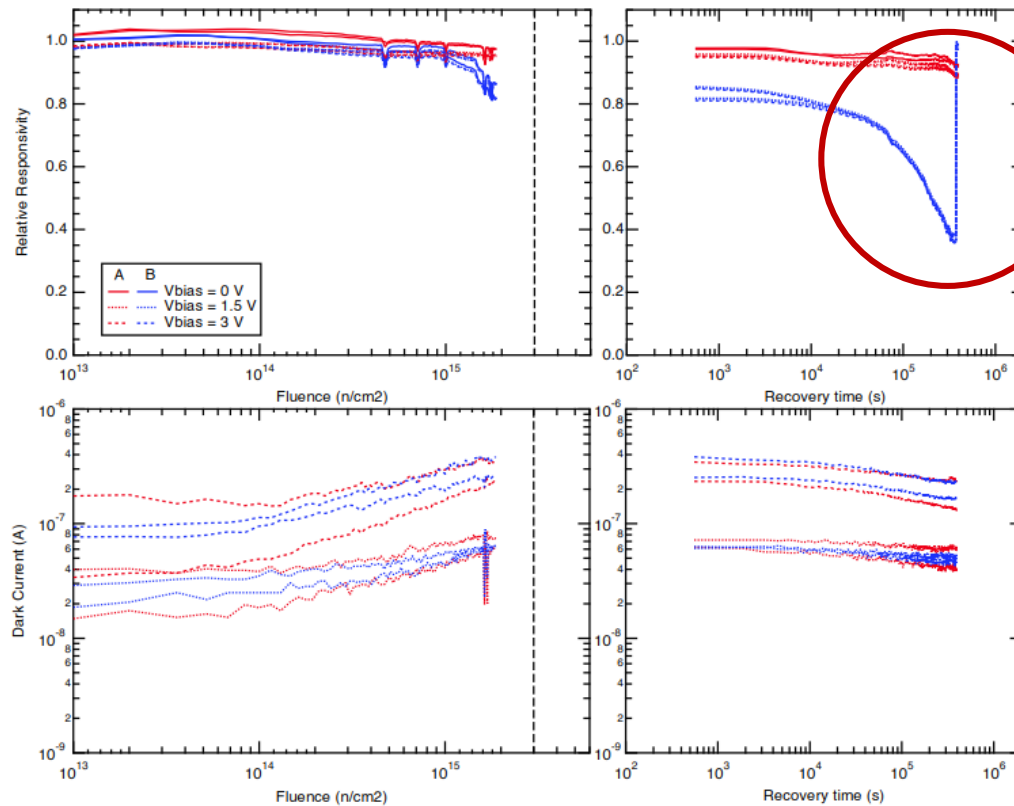


## Displacement damage:



High resistance against TID and displacement damage

# Irradiation tests of SiGe Photodiodes



Change in polarization due to movement and release of sticky tape fixing the optical fiber

# What knowledge have we gained from these tests?

- **Good news first:**

- The photodiodes are very resistant against displacement damage and TID
- Modulators are very resistant against displacement damage
- With increasing the doping concentration and decreasing the etch depth the radiation resistance can be increased → a compromise between radiation resistance and performance has to be found
- Lower temperatures also increase the radiation resistance
- Damage produced through TID in modulators can be annealed by forward biasing

# What knowledge have we gained from these tests?

- **Bad news:**

- Strong degradation of modulators due to TID

**But even if radiation hardness issue could be solved:**

- Long MZM arms and high biases are necessary to achieve good enough phase shift → long MZM arms lead to high losses and with high doping even more → high input power is necessary
- To operate the MZM in the quadrature point an additional control circuit is necessary including heaters → all these points lead to a high power consumption

**Could Ring modulators be an alternative???**

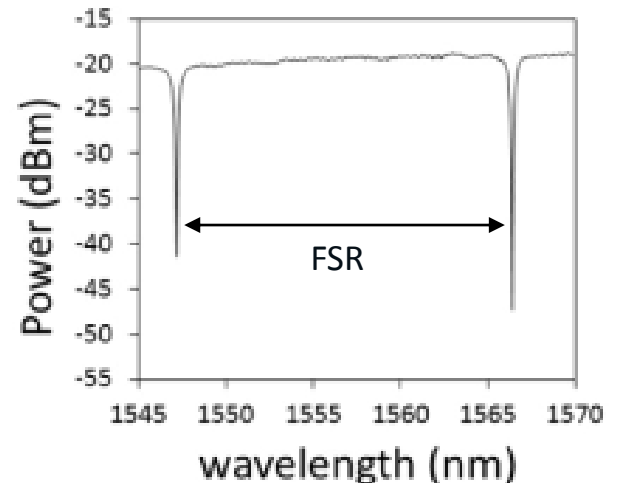
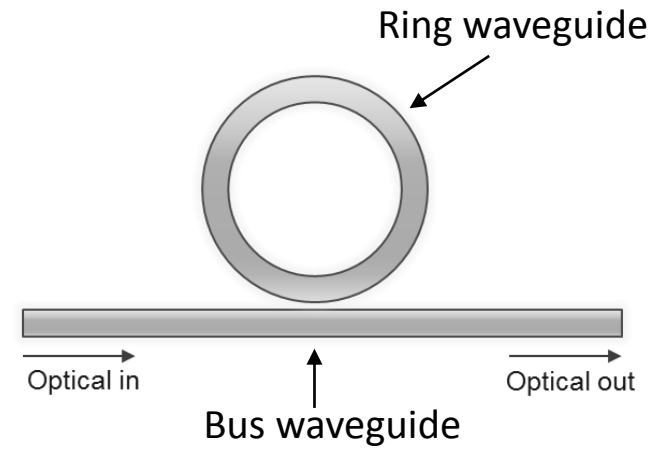


# Ring resonator

- Optical transmission spectrum of the bus waveguide has notches at the ring resonances → light coupled into ring
- Multiple resonances → FSR depends on the resonator length (ring diameter) → the smaller the ring the bigger the FSR
- Resonance occurs when the optical path length is a whole number of wavelengths:

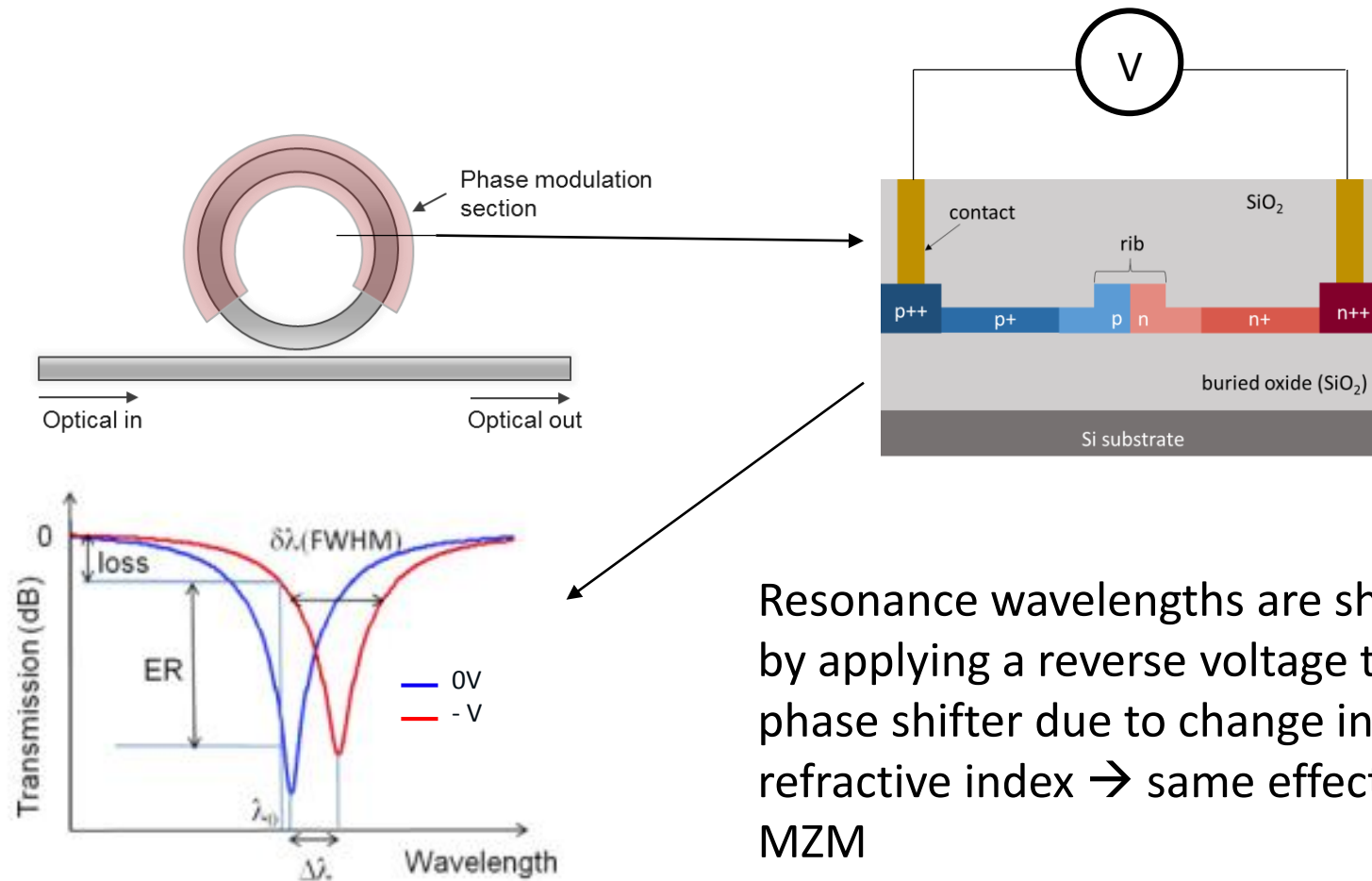
$$\lambda_{res} = \frac{n_{eff}L}{m}, \quad m = 1, 2, 3 \dots$$

- Resonance wavelength is strongly dependent on temperature



# Ring Modulator (RM)

- Ring resonator structure including a phase shifter



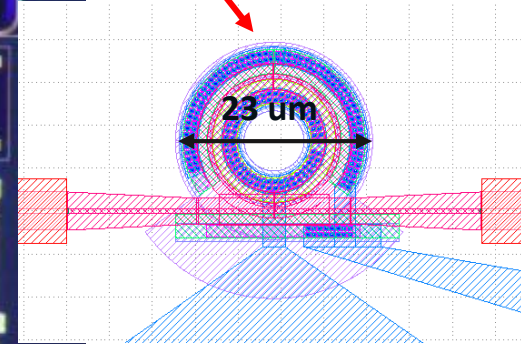
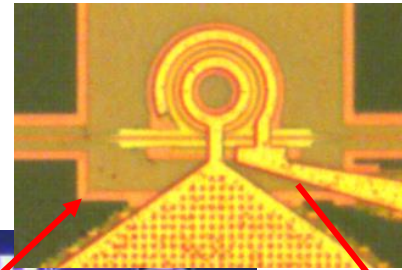
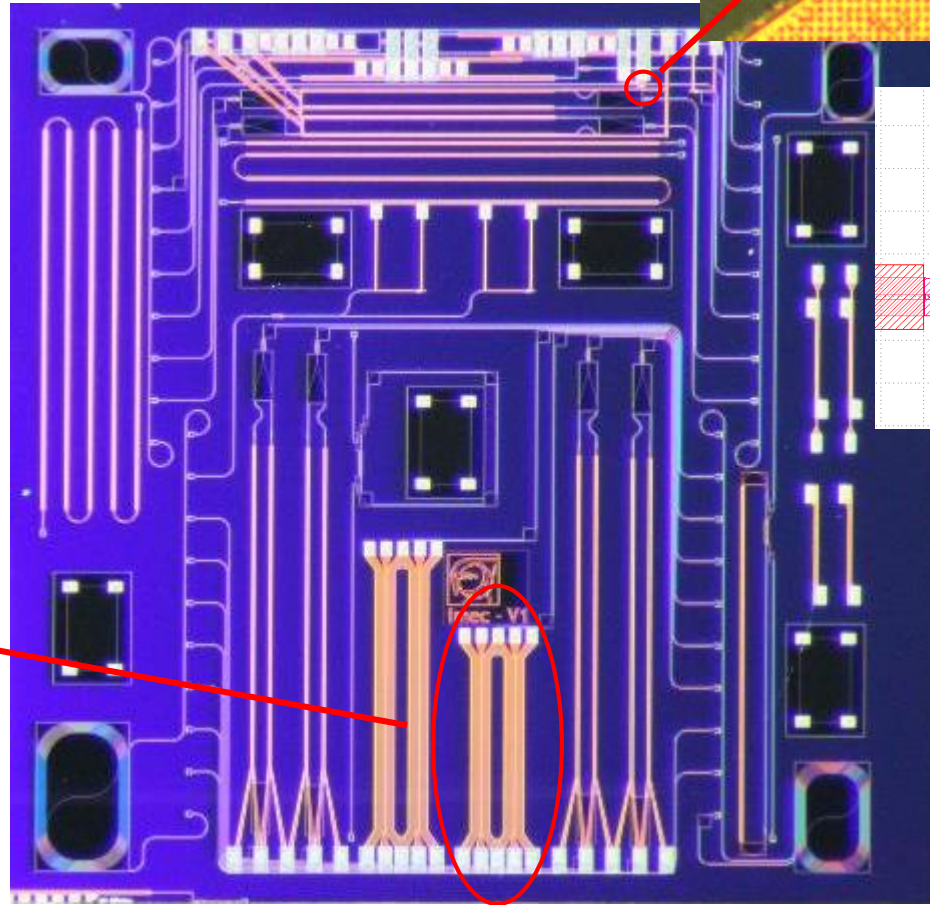
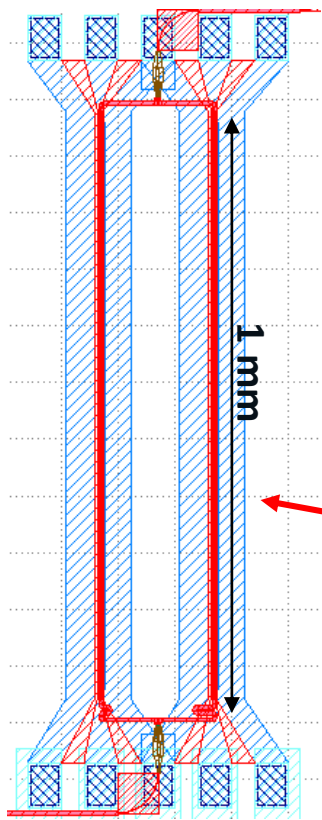


# Advantages of Ring Modulator?

- ☺ Same phase shifter mechanism as MZM → should have similar radiation behavior
  - ☺ More efficient → lower driving voltages needed
  - ☺ Much smaller structure → negligible optical loss and smaller systems
  - ☺ Can be used very efficiently in WDM systems → multi channel integration
  - ☺ Also from foundry site there are a lot of new publications in this direction → general interest increased
  - ☹ Disadvantages: resonance wavelength strongly dependent on temperature and process variations → for compensation a heater is necessary
- So far we only have one RM without heater

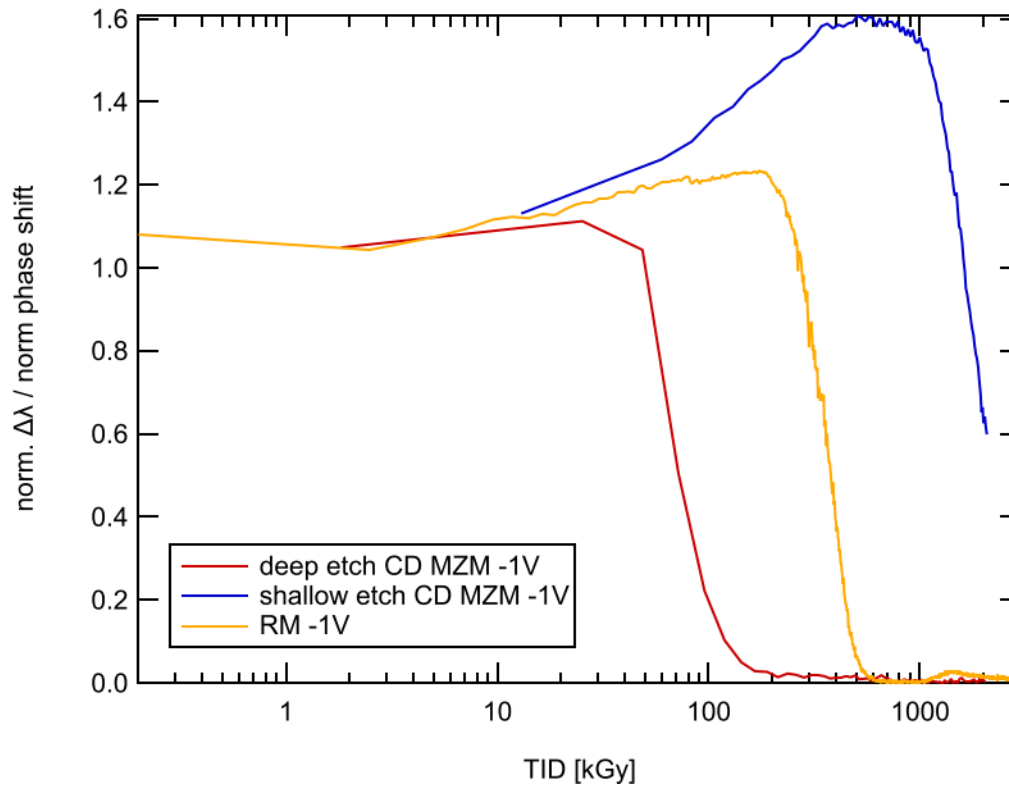


# MZM vs RM

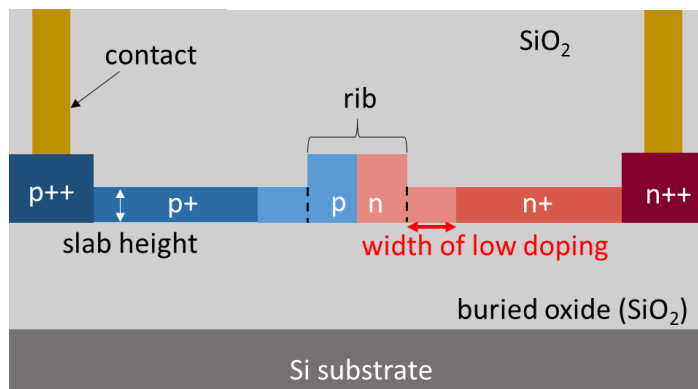
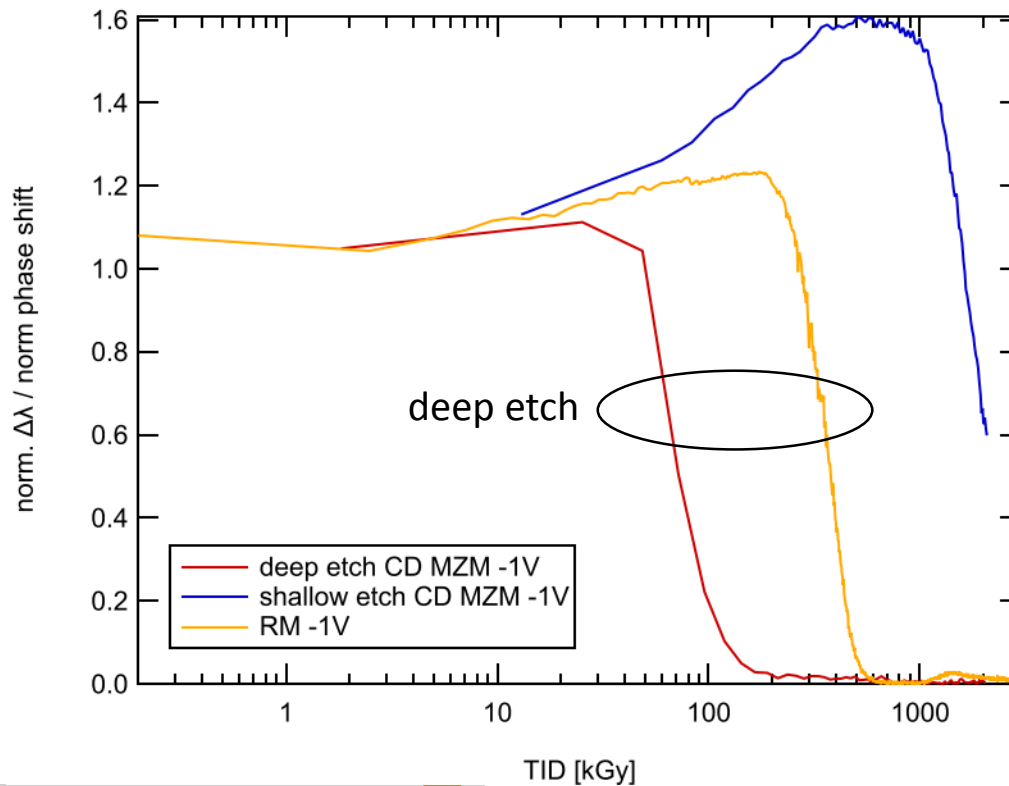


# X-ray test - Ring Modulator

Even without heater we were able to keep the temperature stable enough to do a online irradiation measurement

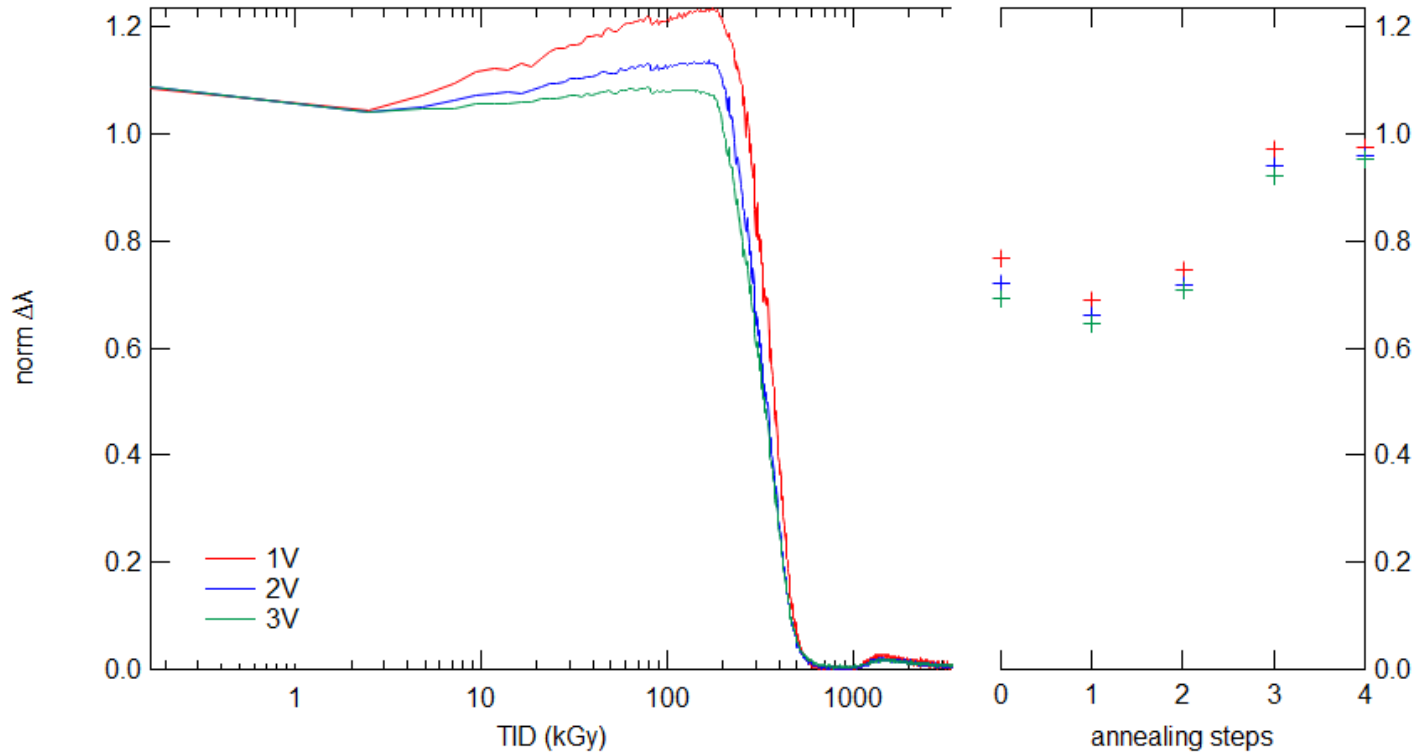


# X-ray test - Ring Modulator



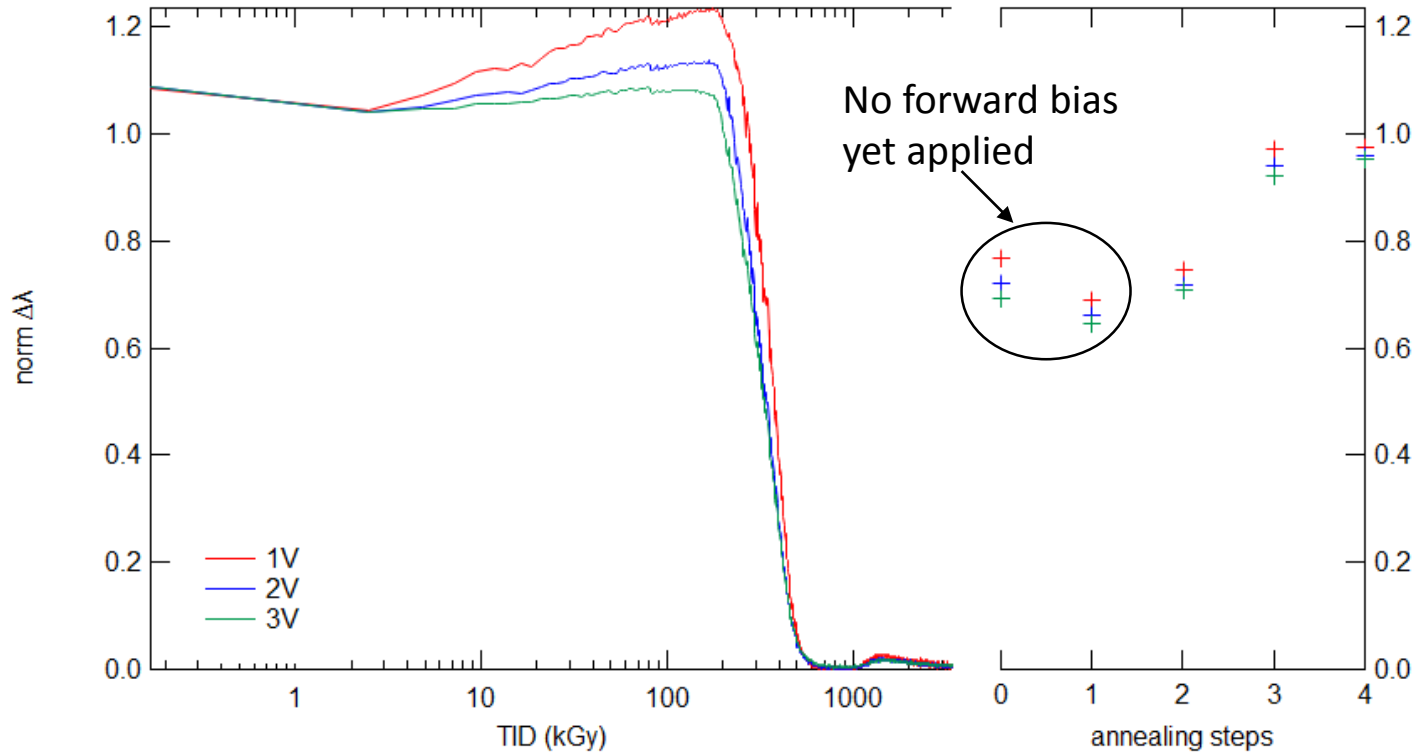
Device	Width of low doping
Deep etch MZM	500 nm
Ring modulator	100 nm

# Annealing Ring Modulator



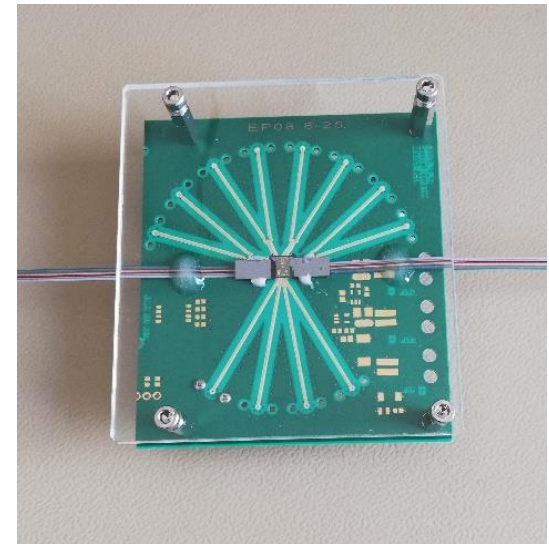
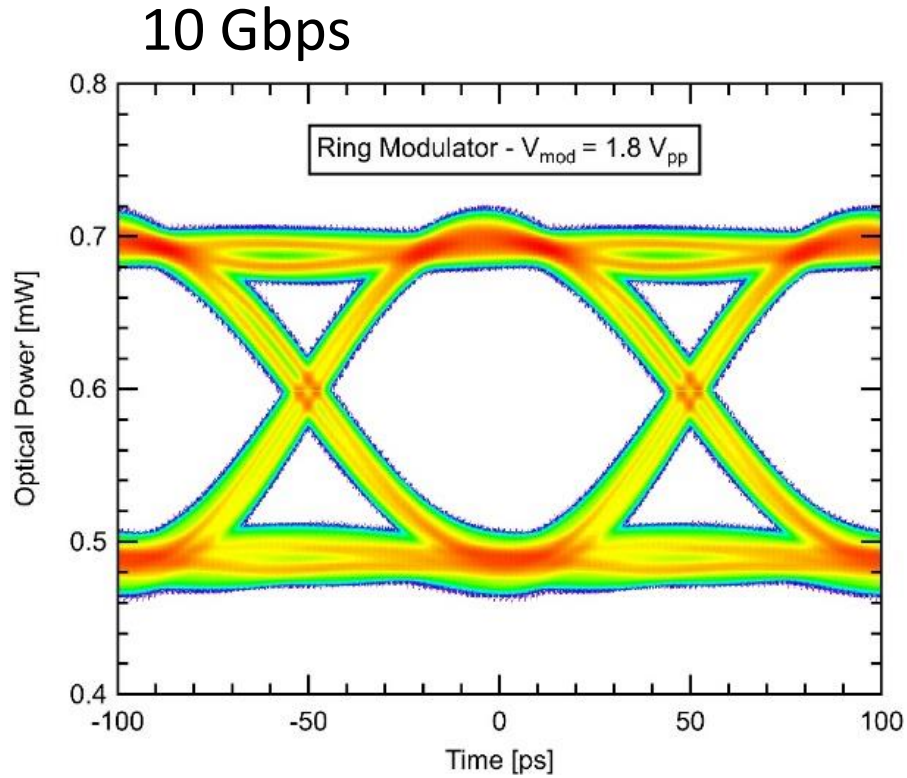
- No forward bias during irradiation
- Annealing step 0: measurement after 2 month of unbiased storage @ RT
- Annealing setp 1: after two days of measurement (no forward bias)
- Annealing step 2: 1 min 50 uA forward current
- Annealing step 3: 1 min 200 uA forward current
- Annealing step 4: 10 min 200 uA forward current

# Annealing Ring Modulator



- No forward bias during irradiation
- Annealing step 0: measurement after 2 month of unbiased storage @ RT
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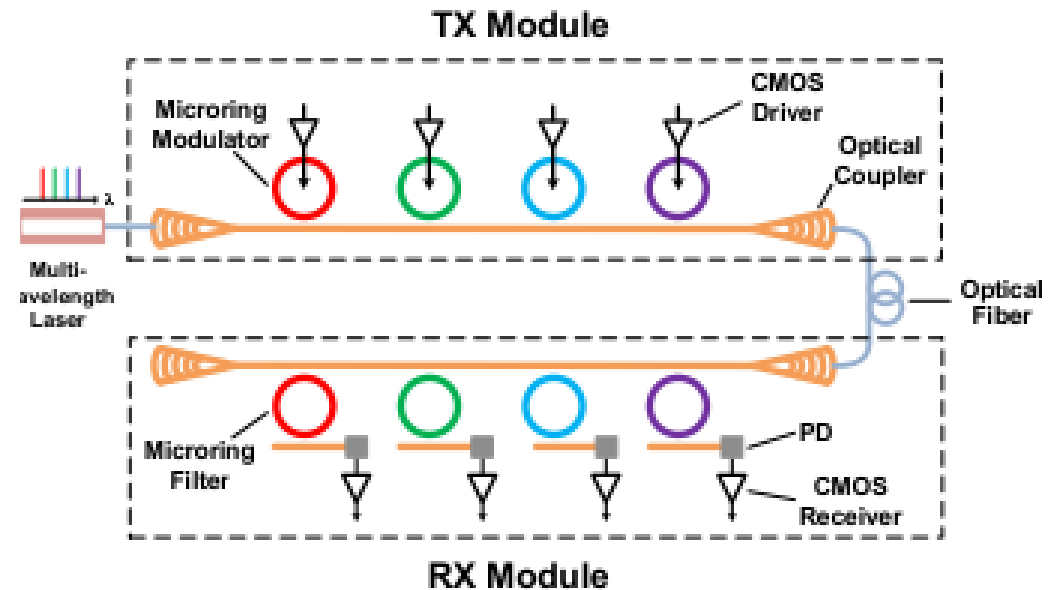
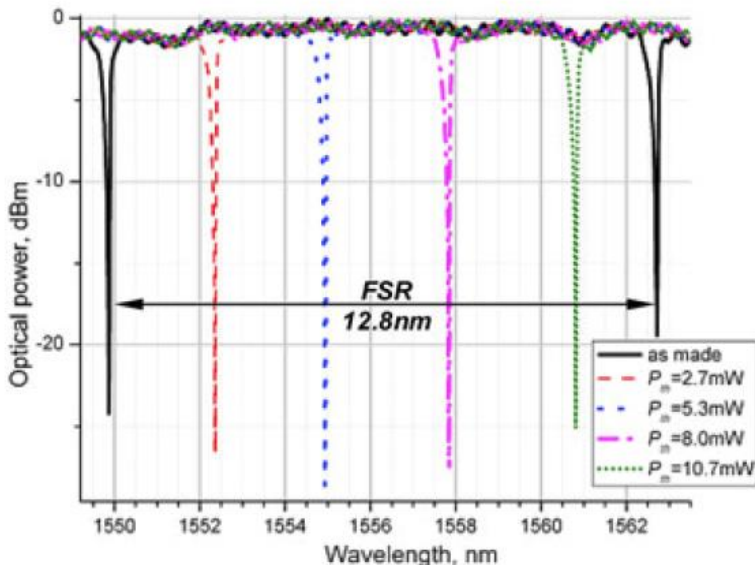
# High speed response Ring Modulator



# RM in Wavelength Division Multiplexing (WDM) systems

- Due to the big FSR, the possibility of tuning the resonant frequency and the small size, RM are very attractive for WDM systems
- RM of varying radii and/or tuned by heater can be cascaded along a waveguide bus to generate WDM optical modulation

Using of a heater to shift the resonance wavelength





# Next steps

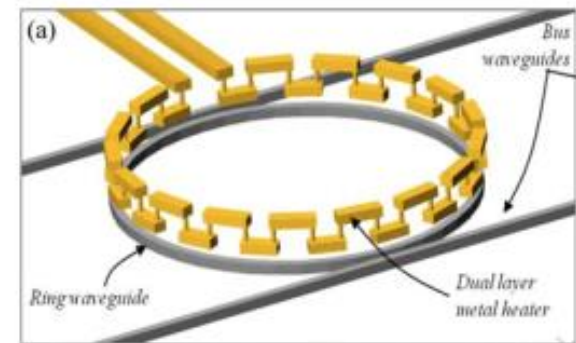
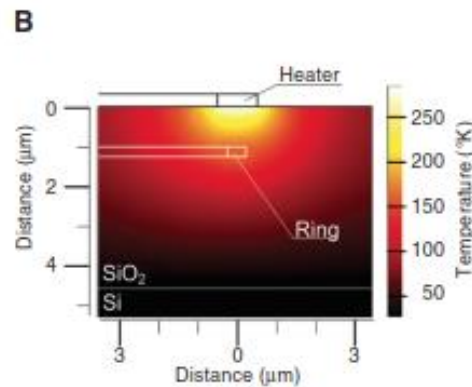
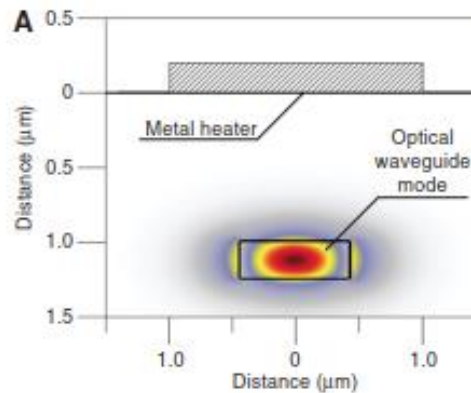
- Only a fraction of measurements are done so far
- Right now we are working on a new test chip
  - Stronger focus on ring modulators
  - Structures on system level
  - WDM test structure
- In order to understand the radiation effects better more intensive focus on the radiation model and the device simulations is needed

Back up slides



# Tuning of ring modulators - heaters

- Use of resistive structures → nichrome, titanium or doped silicon → running current through these structures creates heat
- Most common configuration → heater on top of ring



- Separation between heater and ring to protect optical mode → not optimal tuning efficiency